

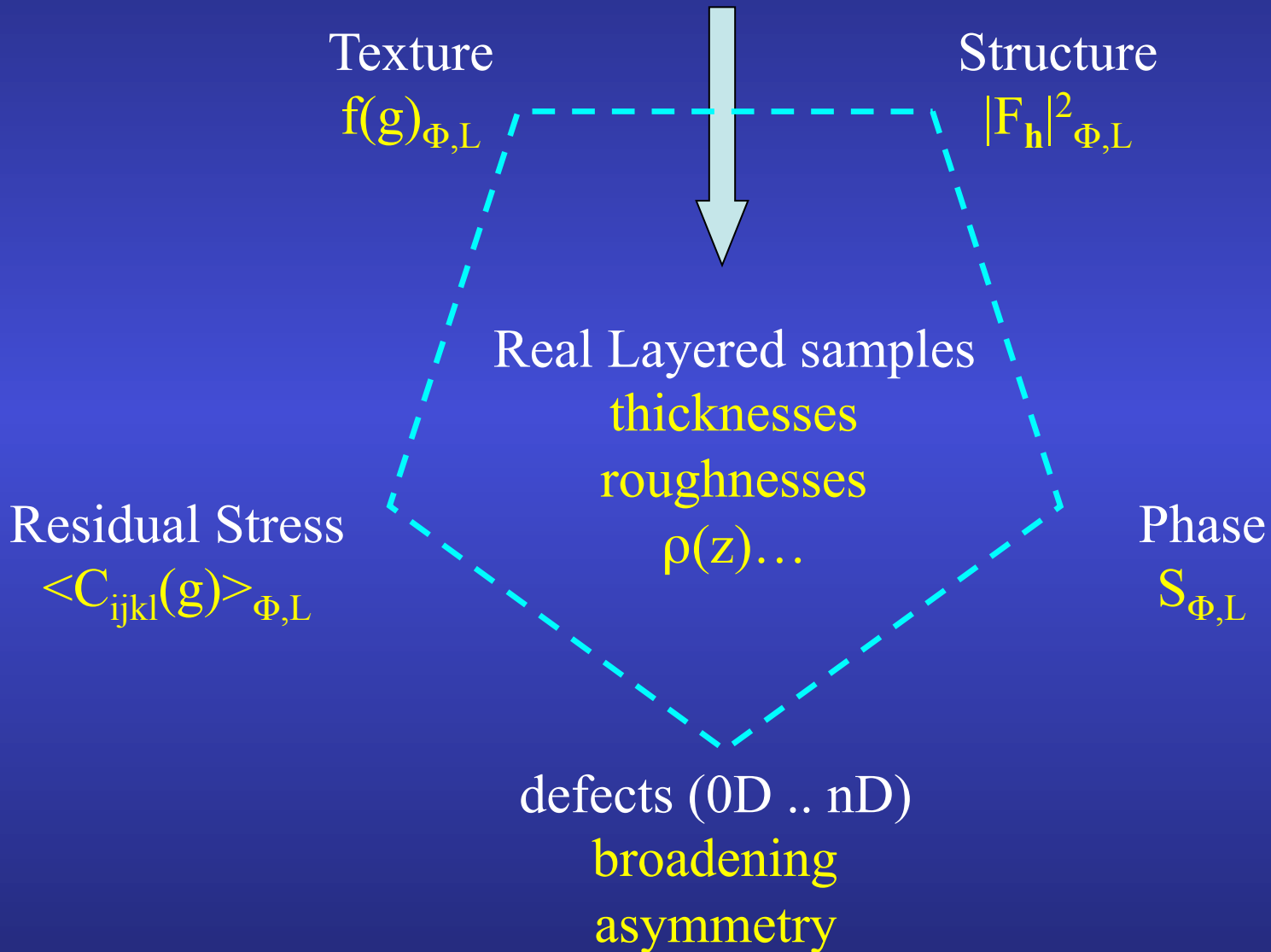


Une approche globale pour caractériser les architectures minces: l'Analyse Combinée par diffraction-diffusion

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Problematic



Structure determination on real (textured) samples

Problem 1

Structure and QTA: correlations ?

$f(g)$ and $|F_h|^2$ are different !

$f(g)$:

- Angularly constrained: $[h_1k_1l_1]^*$ and $[h_2k_2l_2]^*$ make a given angle: more determined if F^2 high
- lot of data (spectra) needed

$|F_h|^2$:

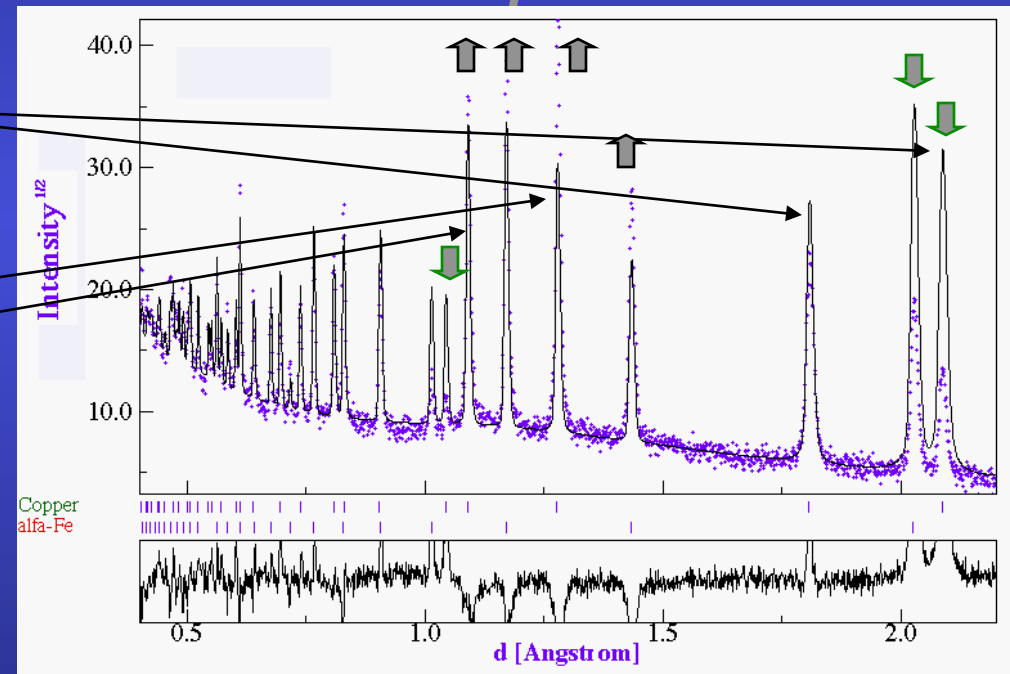
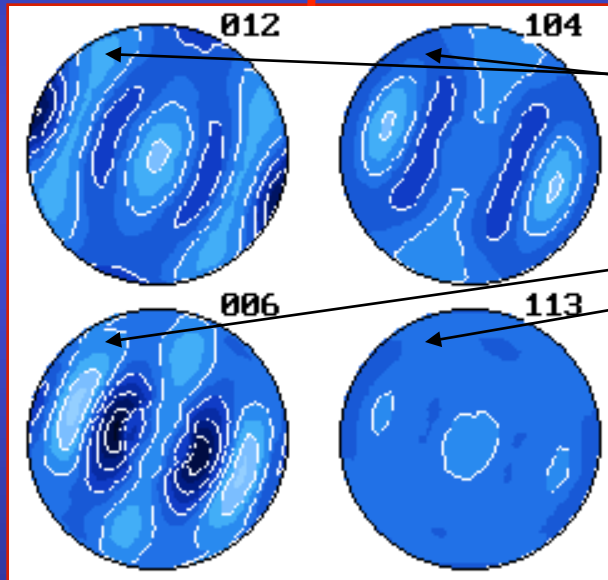
- Position, f_i , and Debye-Waller constrained
- work on the sum of all diagrams on average

Texture from Spectra

Orientation Distribution Function (ODF)

From pole figures

From spectra



Le Bail extraction + ODF: WMV, E-WIMV, Generalized spherical harmonics, components, ADC, entropy maximisation ...

Rietveld: extended to lots of spectra

$$y_c(\mathbf{y}_S, \theta, \eta) = y_b(\mathbf{y}_S, \theta, \eta) + I_0 \sum_{i=1}^{N_L} \sum_{\Phi=1}^{N_\Phi} \frac{v_{i\Phi}}{V_{c\Phi}} \sum_h L_p(\theta) j_{\Phi h} |F_{\Phi h}|^2 \Omega_{\Phi h}(\mathbf{y}_S, \theta, \eta) P_{\Phi h}(\mathbf{y}_S, \theta, \eta) A_{i\Phi}(\mathbf{y}_S, \theta, \eta)$$

Texture

$$P_k(\chi, \phi) = \int_{\varphi} f(\mathbf{g}, \varphi) d\varphi$$

- Generalized Spherical Harmonics (Bunge):

$$P_k(\chi, \phi) = \sum_{l=0}^{\infty} \frac{1}{2l+1} \sum_{n=-l}^l k_l^n(\chi, \phi) \sum_{m=-l}^l C_l^{mn} k_n^{*m}(\Theta_k \phi_k)$$

$$f(\mathbf{g}) = \sum_{l=0}^{\infty} \sum_{m,n=-l}^l C_l^{mn} T_l^{mn}(\mathbf{g})$$

- Components (Helming):

$$f(\mathbf{g}) = F + \sum_c I^c f^c(\mathbf{g})$$

- WIMV (William, Imhof, Matthies, Vinel) iterative process:

$$f^{n+1}(\mathbf{g}) = N_n \frac{f^n(\mathbf{g})f^0(\mathbf{g})}{\left(\prod_{\mathbf{h}=1}^I \prod_{m=1}^{M_h} P_{\mathbf{h}}^n(\mathbf{y}) \right)^{\frac{1}{IM_h}}}$$

$$f^0(\mathbf{g}) = N_0 \left(\prod_{\mathbf{h}=1}^I \prod_{m=1}^{M_h} P_{\mathbf{h}}^{\text{exp}}(\mathbf{y}) \right)^{\frac{1}{IM_h}}$$

E-WIMV (Rietveld only):

with $0 < r_n < 1$, relaxation parameter,
 M_h number of division points of the integral
 around k ,
 w_h reflection weight

$$f^{n+1}(\mathbf{g}) = f^n(\mathbf{g}) \prod_{m=1}^{M_h} \left(\frac{P_{\mathbf{h}}(\mathbf{y})}{P_{\mathbf{h}}^n(\mathbf{y})} \right)^{r_n \frac{w_h}{M_h}}$$

- Entropy maximisation (Schaeben):

$$f^{n+1}(\mathbf{g}) = f^n(\mathbf{g}) \prod_{m=1}^{M_h} \left(\frac{P_{\mathbf{h}}(\mathbf{y})}{P_{\mathbf{h}}^n(\mathbf{y})} \right)^{\frac{r_n}{M_h}}$$

- arbitrarily defined cells (ADC, Pawlik): Very similar to E-WIMV, with integrals along path tubes

Residual Stresses shift peaks with γ

Problem 2

Stress and QTA: correlations ? $f(g)$ and $\langle C_{ijkl} \rangle$

$f(g)$:

- Moves the $\sin^2\Psi$ law away from linear relationship
- Needs the integrated peak (full spectra)

strains:

- Measured with pole figures
- needs the mean peak position

Isotropic samples: triaxial, biaxial, uniaxial stress states

Textured samples: Reuss, Voigt, Hill, Bulk geometric mean approaches

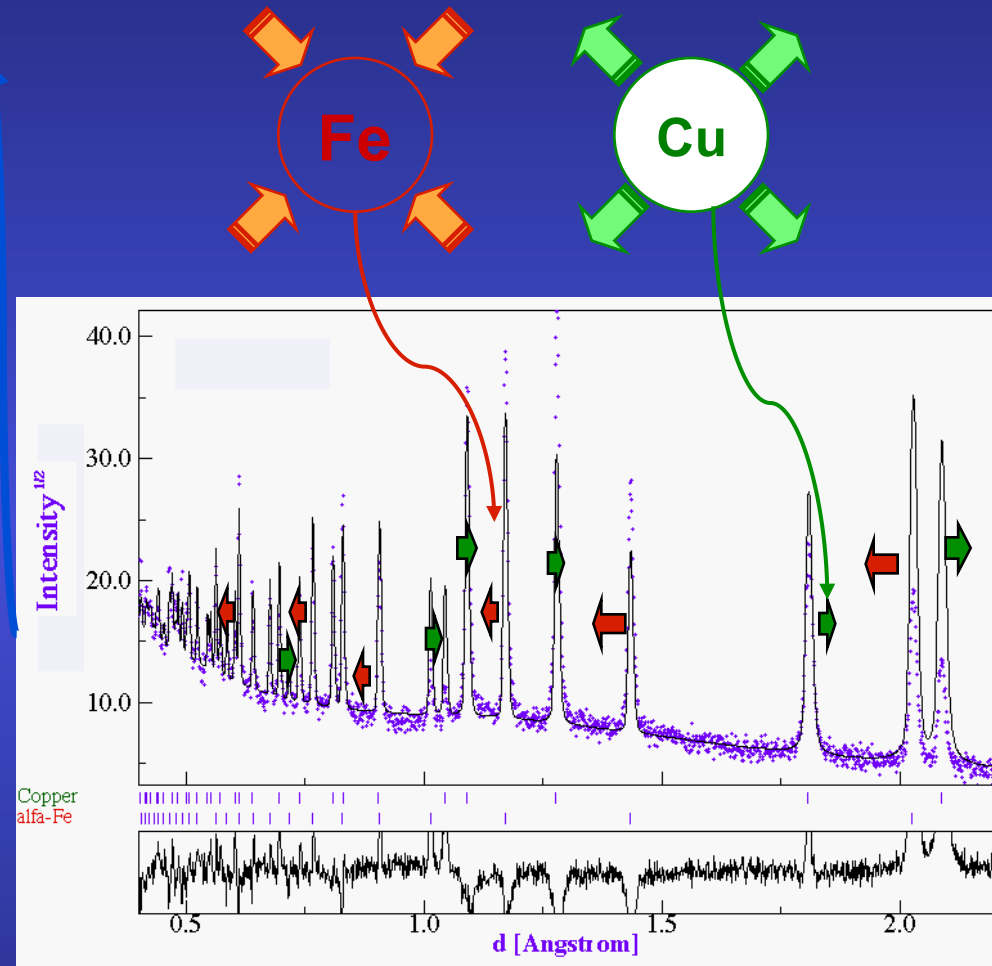
Residual Stresses and Rietveld

- Macro elastic strain tensor (I kind)
- Crystal anisotropic strains (II kind)

C

Macro and micro stresses

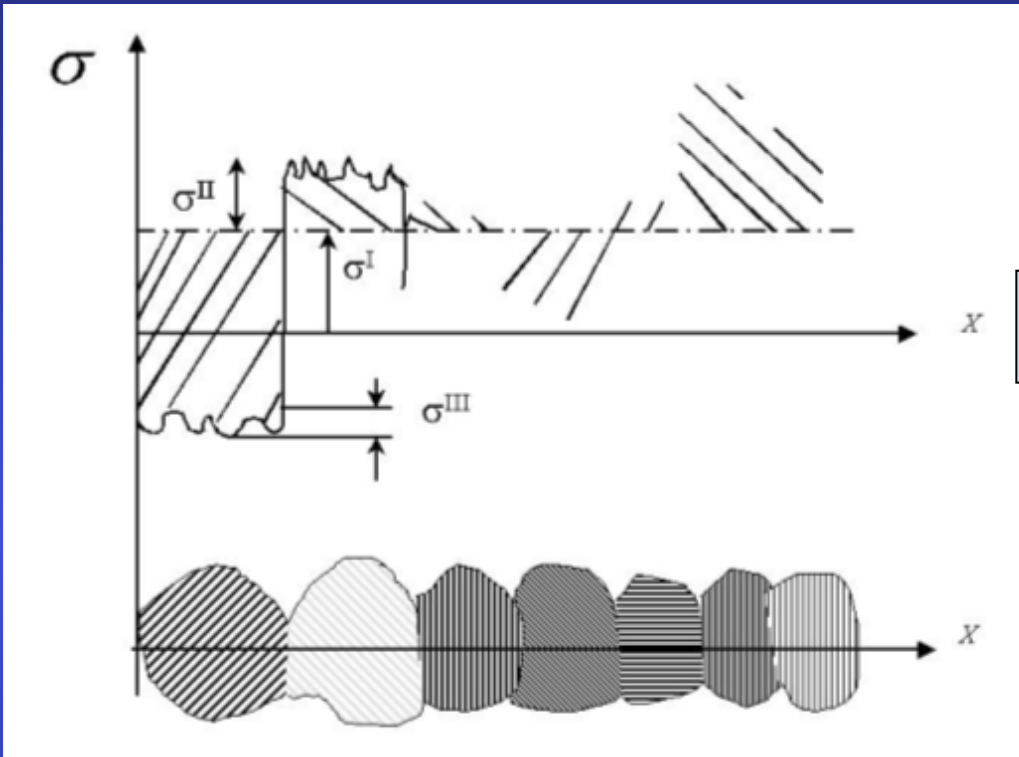
Applied macro stresses



Isotropic samples: triaxial, biaxial, uniaxial stress states

Textured samples: Reuss, Voigt, Hill, Bulk geometric mean approaches

Strain-Stress



$$\boldsymbol{\varepsilon}(\mathbf{X}) = \boldsymbol{\varepsilon}^I + \boldsymbol{\varepsilon}^{II}(\mathbf{X}) + \boldsymbol{\varepsilon}^{III}(\mathbf{X})$$

$$\langle S \rangle_{\text{geo}}^{-1} = \exp \left[- \sum_{m=1}^N v_m \ln S_m \right] = \exp \left[\sum_{m=1}^N v_m \ln S_m^{-1} \right] = \langle S^{-1} \rangle_{\text{geo}} = \langle C \rangle_{\text{geo}}$$

or

$$\langle S \rangle_{\text{geo}}^{-1} = \left[\prod_{m=1}^N S_m^{v_m} \right]^{-1} = \prod_{m=1}^N S_m^{-v_m} = \prod_{m=1}^N (S_m^{-1})^{v_m} = \langle S^{-1} \rangle_{\text{geo}} = \langle C \rangle_{\text{geo}}$$

Layered systems

Problem 3

Layer, Rietveld and QTA: correlations: $f(g)$, thicknesses and structure

$f(g)$:

- Pole figures need corrections for abs-vol
- Rietveld also to correct intensities

layers:

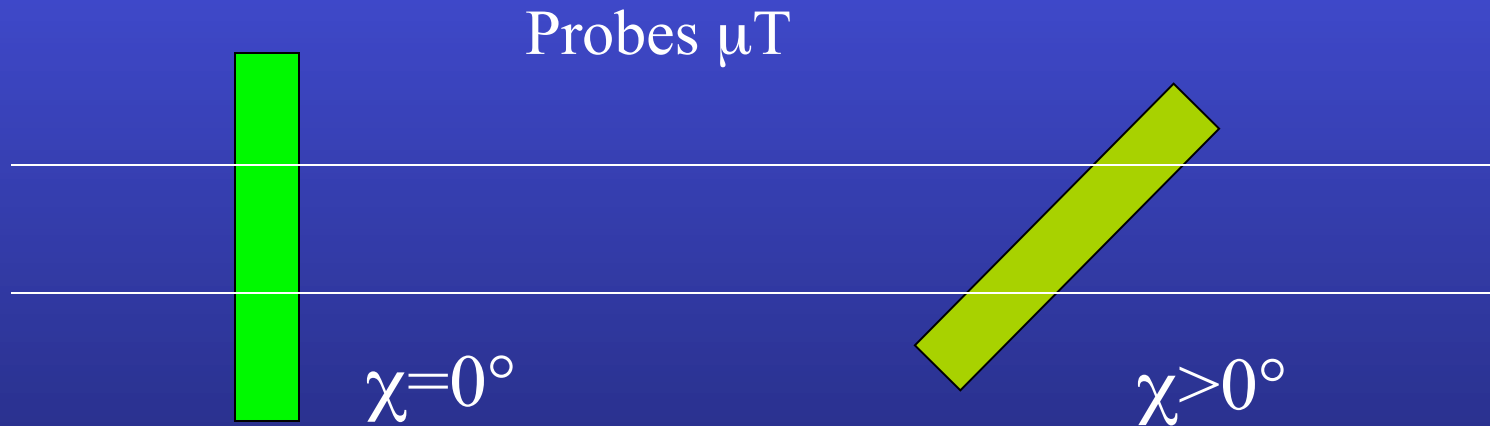
- unknown sample true absorption coefficient μ
- unknown effective thickness (porosity)

Layering

Asymmetric Bragg-Brentano

$$C_{\chi}^{\text{top film}} = g_1 (1 - \exp(-\mu T g_2 / \cos \chi)) / (1 - \exp(-2\mu T / \sin \omega \cos \chi))$$

$$C_{\chi}^{\text{cov. layer}} = C_{\chi}^{\text{top film}} \left(\exp(-g_2 \sum \mu'_i T'_i / \cos \chi) \right) / \left(\exp(-2 \sum \mu'_i T'_i / \sin \omega \cos \chi) \right)$$



Phase and Texture

Problem 4

Phase and QTA: correlations: $f(g)$, S_{Φ}

$f(g)$:

- angular relationships
- plays on individual spectra
- essential to operate on textured sample

S_{Φ} :

- plays on overall scale factor (sum diagram)

Phase analysis

- Volume fraction

$$V_{\Phi} = \frac{S_{\Phi} V_{uc\Phi}^2}{\sum_{\Phi} (S_{\Phi} V_{uc\Phi}^2)_{\Phi}}$$

- Weight fraction

$$m_{\Phi} = \frac{S_{\Phi} Z_{\Phi} M_{\Phi} V_{uc\Phi}^2}{\sum_{\Phi} (S_{\Phi} Z_{\Phi} M_{\Phi} V_{uc\Phi}^2)_{\Phi}}$$

Z = number of formula units

M = mass of the formula unit

V = cell volume

Structure and Residual Stresses (shift peaks with \mathbf{y})

Problem 5

Stress and cell parameters: correlations: peak positions and C_{ijkl}

Cell parameters:

- Measured at high angles
- Bragg law evolution

strains:

- Measured precisely at high angles
- stiffness-based variation, also with Ψ

Shapes, microstrains, defaults, distributions

Problem 6

Shapes and stress-texture-structure: correlations ?

Shapes:

- line broadening problem
- average positions modified
- if anisotropic: modification changes with γ

Stress-texture-structure:

- need “true” peak positions and intensities
- need deconvoluted signals

Why not benefit of texture in Structure determination ?

Perfect powders:

- overlaps (intra- and inter-
- no angular constrain
- anisotropy difficult to res

Single pattern

Single crystals:

- reduced overlaps
- max angular constrains
- Perfect texture: max anisotropy

Many individual diffracted peaks

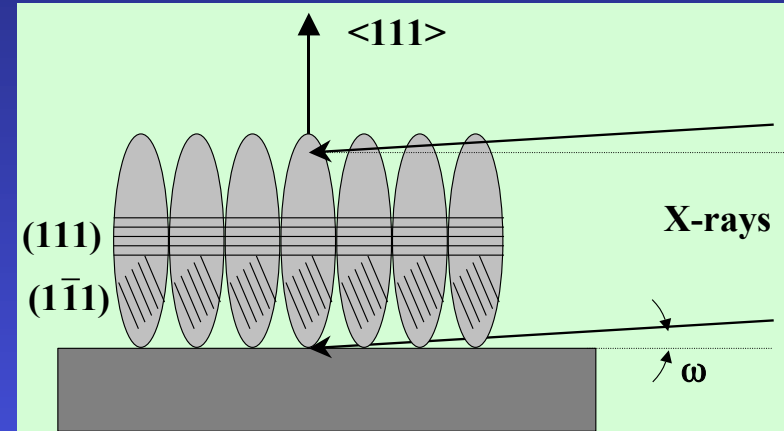
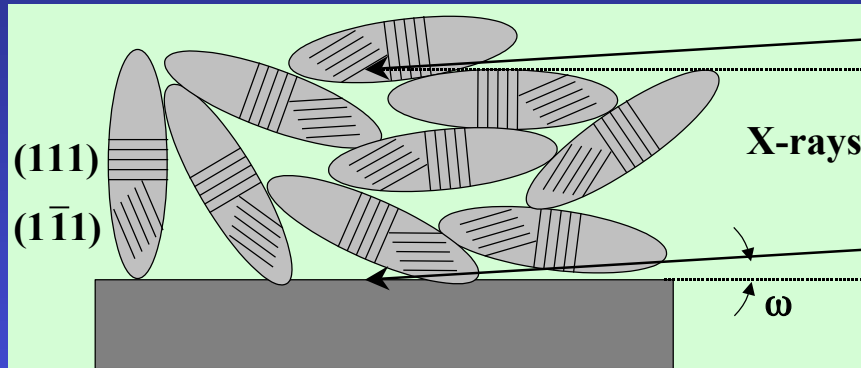
Textured powders:

- reduced overlaps
- angular constrain = $f(\text{texture strength})$
- Intermediate anisotropy

Many patterns to measure and analyse

Line Broadening:

Crystallite sizes, shapes, μ strains, distributions



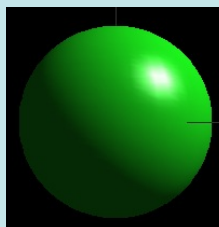
- Texture helps the "real" mean shape determination
- Modelled by peak convolution + Popa formalism

$$\langle R_h \rangle = R_0 + R_1 P_2^0(x) + R_2 P_2^1(x) \cos \varphi + R_3 P_2^1(x) \sin \varphi + R_4 P_2^2(x) \cos 2\varphi + R_5 P_2^2(x) \sin 2\varphi +$$

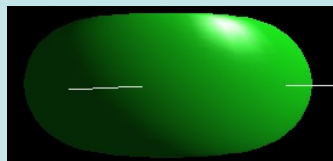
$$\langle \epsilon_h^2 \rangle E_h^4 = E_1 h^4 + E_2 k^4 + E_3 \ell^4 + 2E_4 h^2 k^2 + 2E_5 \ell^2 k^2 + 2E_6 h^2 \ell^2 + 4E_7 h^3 k + 4E_8 h^3 \ell + 4E_9 k^3 h +$$

$$4E_{10} k^3 \ell + 4E_{11} \ell^3 h + 4E_{12} \ell^3 k + 4E_{13} h^2 k \ell + 4E_{14} k^2 h \ell + 4E_{15} \ell^2 k h$$

$\bar{1}$



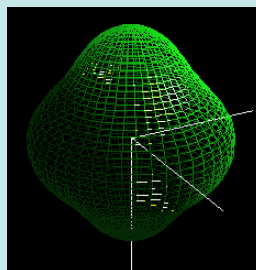
R_0



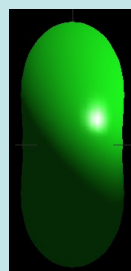
$R_0, R_1 < 0$



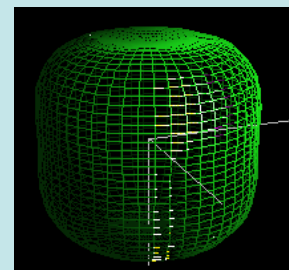
$R_0, R_1 > 0$



$R_0, R_6 > 0$

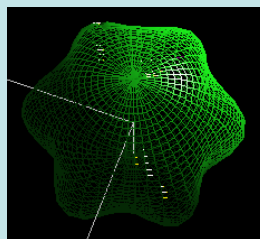


$R_0,$
 R_2 and $R_6 > 0$

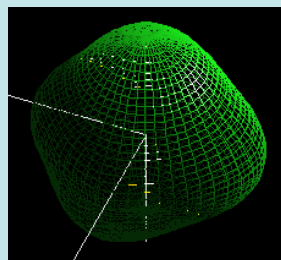


$R_0, R_6 < 0$

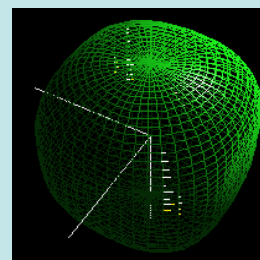
$6/m$



$R_0, R_4 > 0$



$R_0, R_1 > 0$

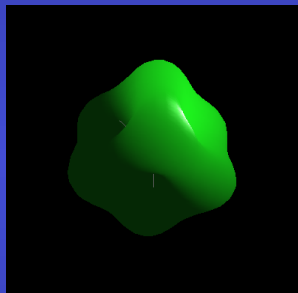


$R_0, R_1 < 0$

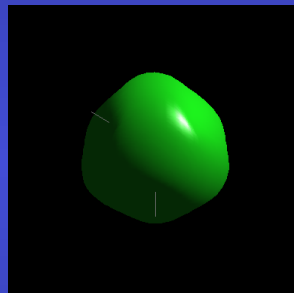
$m\bar{3}m$

Gold thin films

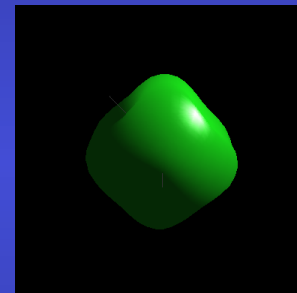
| Crystallite size (Å) along | Film thickness | | | | | |
|----------------------------|----------------|------|------|------|------|------|
| | 10nm | 15nm | 20nm | 25nm | 35nm | 40nm |
| [111] | 176 | 153 | 725 | 254 | 343 | 379 |
| [200] | 64 | 103 | 457 | 173 | 321 | 386 |
| [202] | 148 | 140 | 658 | 234 | 337 | 381 |



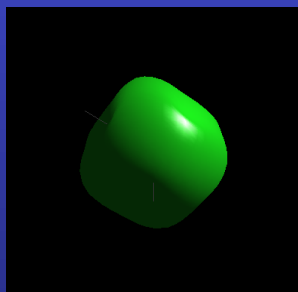
10 nm



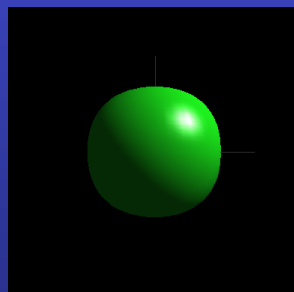
15 nm



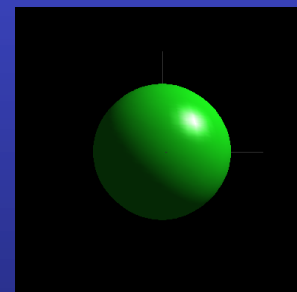
20 nm



25 nm



35 nm



40 nm

Why not grinding samples another problem !

Grinding: removes angular relationship, adds correlations

Texture:

- not measured
- removed ? hope to get a perfect powder

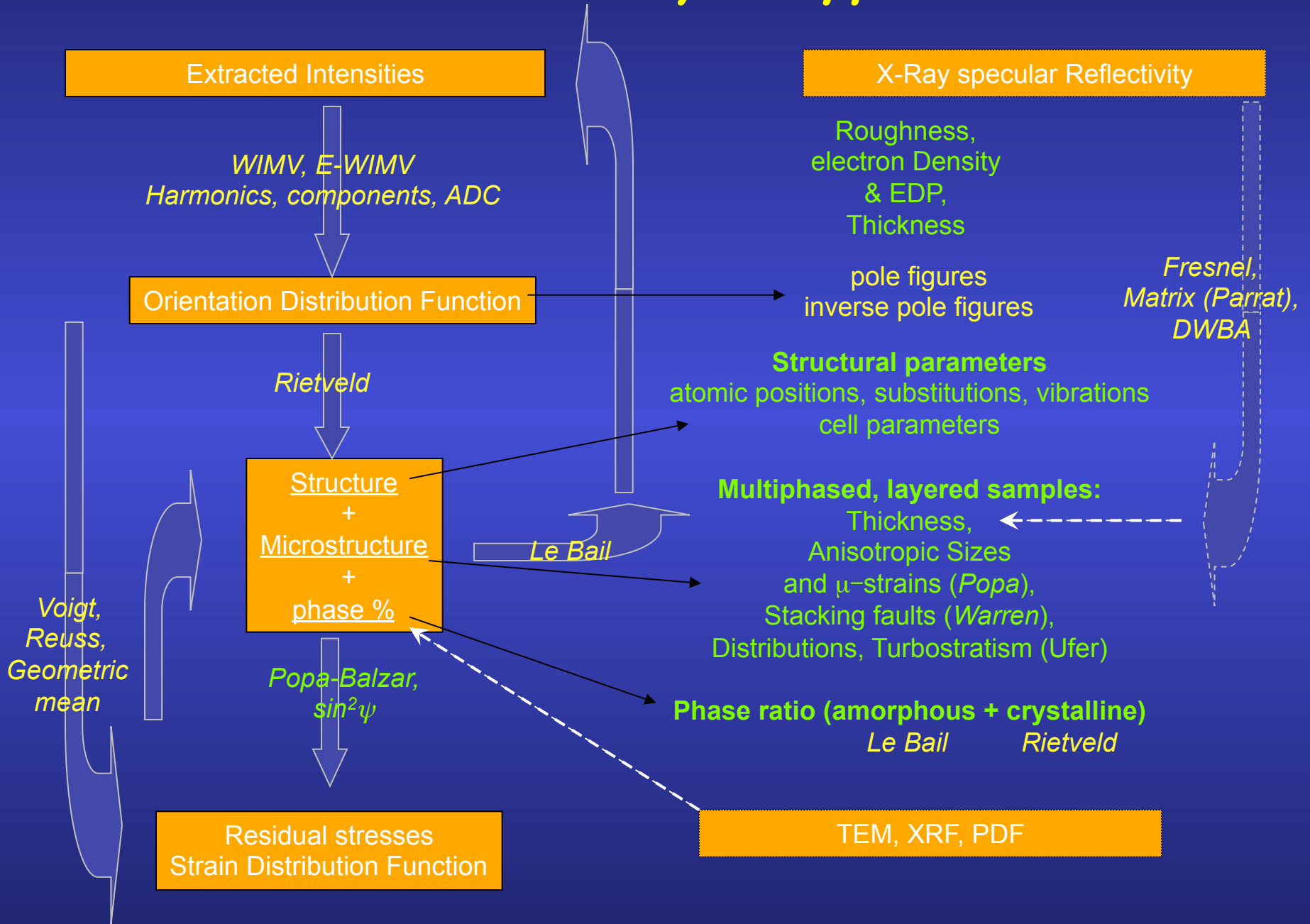
Strains, defaults, anisotropy ... :

- some removed, some added

Same sample ?

Rare samples ?

Combined Analysis approach



Minimization algorithms

- Can be fully used in the method (everywhere)
- **Marquardt Least Squares** (based on steepest decrease and Gauss-Newton)
 - Efficient, best with few parameters, near the solution
- **Evolutionary computation** (or genetic algorithm)
 - Slow, not efficient, requires a lot of resources
 - Unlimited number of parameters
 - Can start far from the solution
- **Simulated annealing** (the solution proceed like a random walk, but the walking step decreases as temperature decreases)
 - In between the Marquardt and evolutionary algorithms
- **Simplex** (generates $n+1$ starting solutions as vertices of a polygon, n number of parameters, and contract/expand the polygon around the minima)
 - Slow on convergence
 - Remains close to the solution, but explore more minima with respect to the Marquardt

Minimum experimental requirements

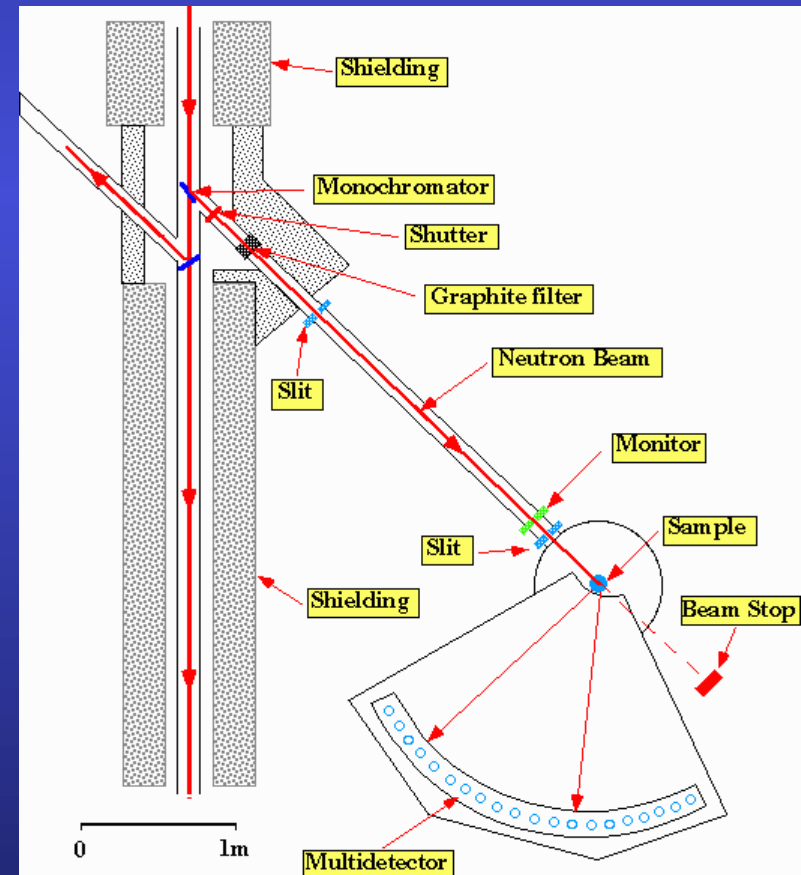
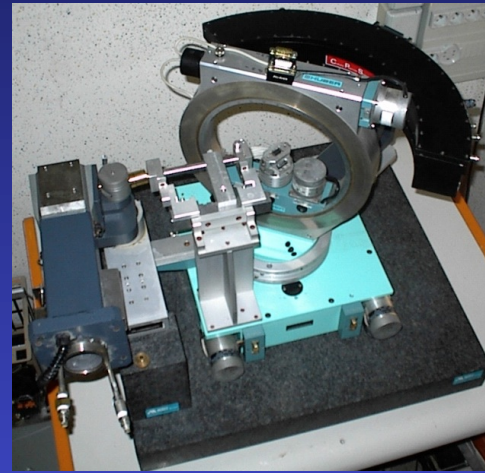
1D or 2D Detector + 4-circle diffractometer
(X-rays and neutrons)
CRISMAT, ILL

+

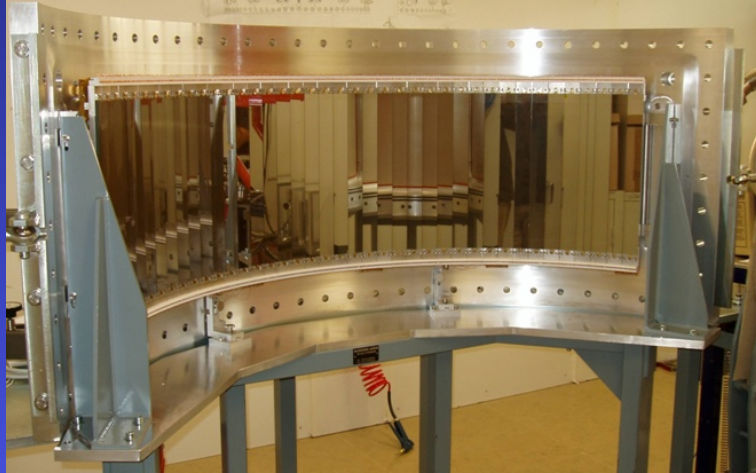
~1000 experiments (2θ diagrams)
in as many sample orientations

+

Instrument calibration
(peaks widths and shapes,
misalignments, defocusing ...)



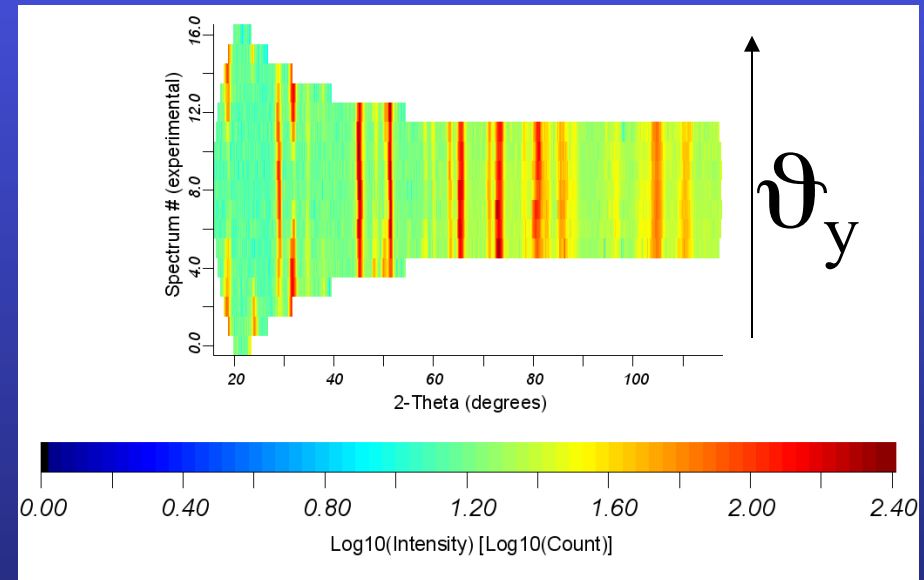
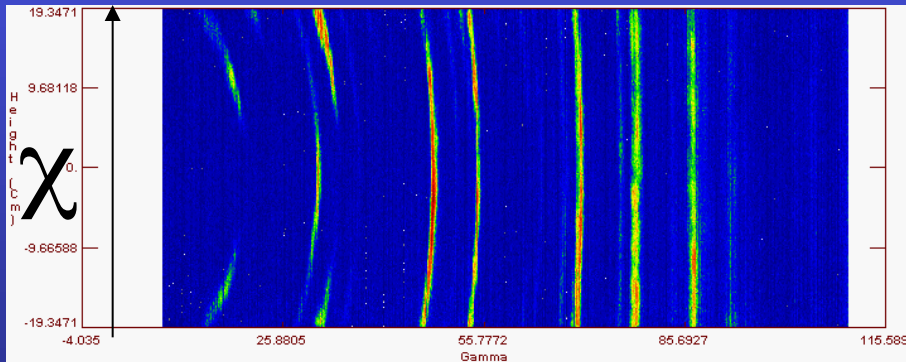
2D Curved Area Position Sensitive Detector



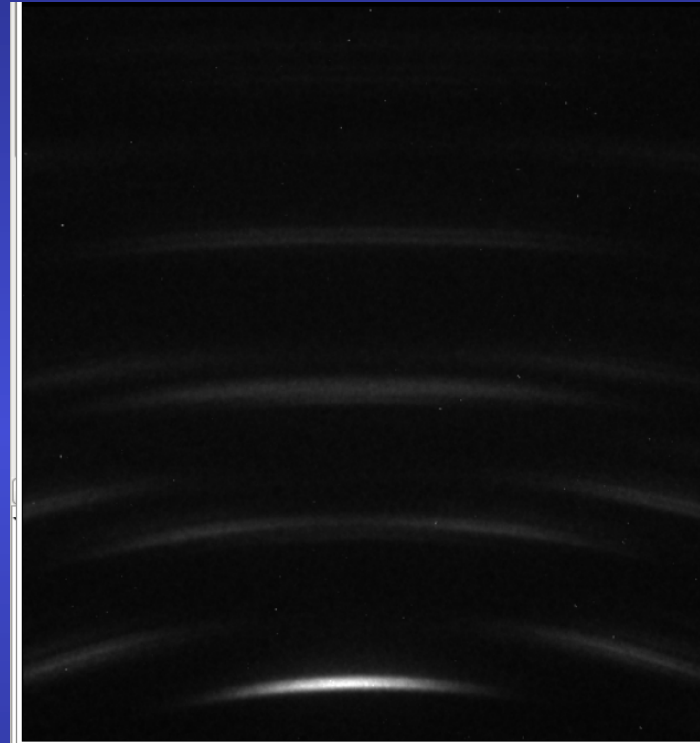
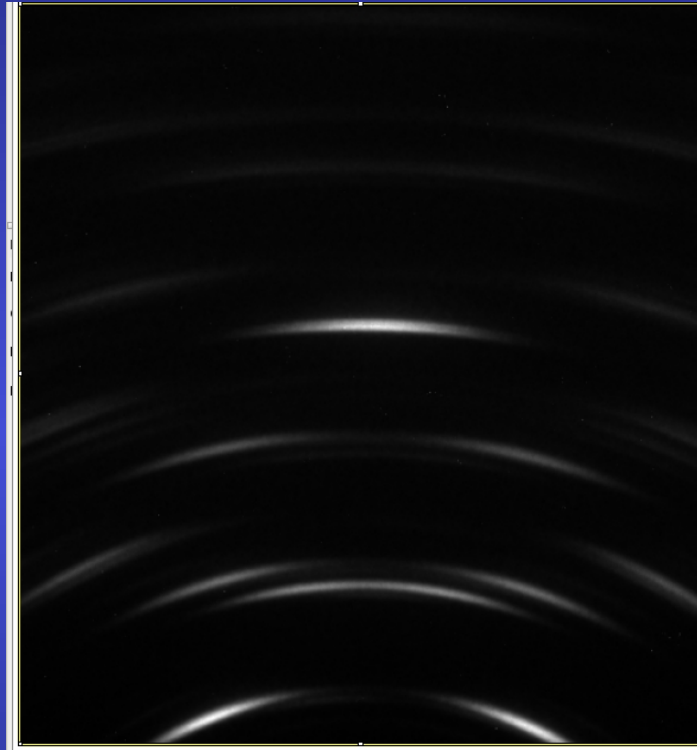
D19 - ILL

+

~100 experiments (2D Debye-Scherrer diagrams)
in as many sample orientations



Bruker CCD + «small» InCoatec μ source



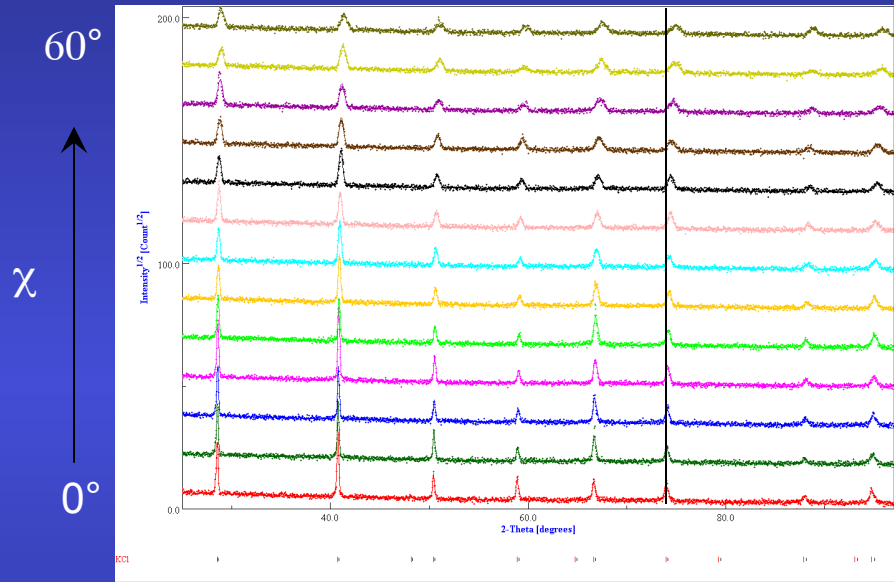
Reflection geometry
72 images
2-hours acquisition
60 mm sample-CCD distance



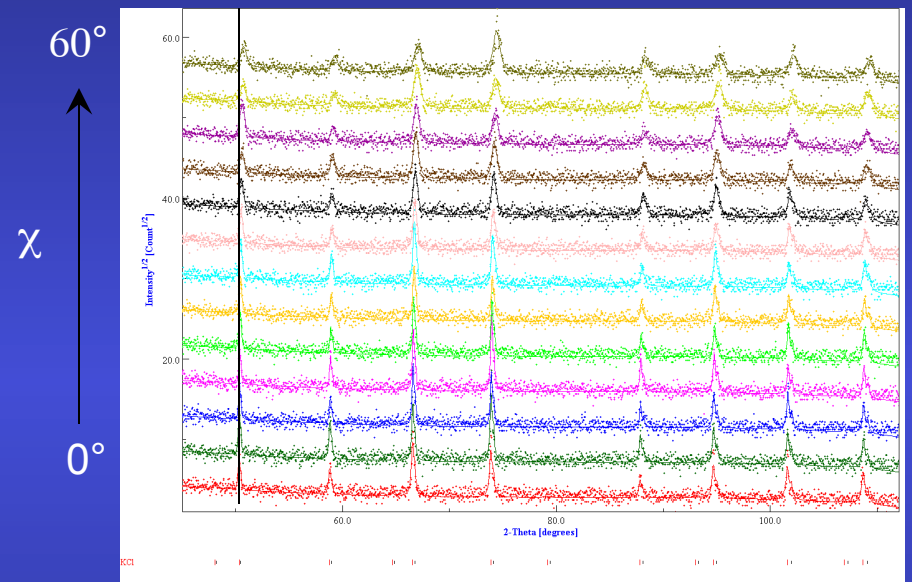
Compromises:
- resolution/pole figure coverage
- pixel size/distance
- wavelength/nb of lines

Calibration

$\omega = 20^\circ$



$\omega = 40^\circ$



KCl, LaB₆ ...



FWHM (ω , χ , 2θ , η ...)
2 θ shift
gaussianity
asymmetry
misalignments ...

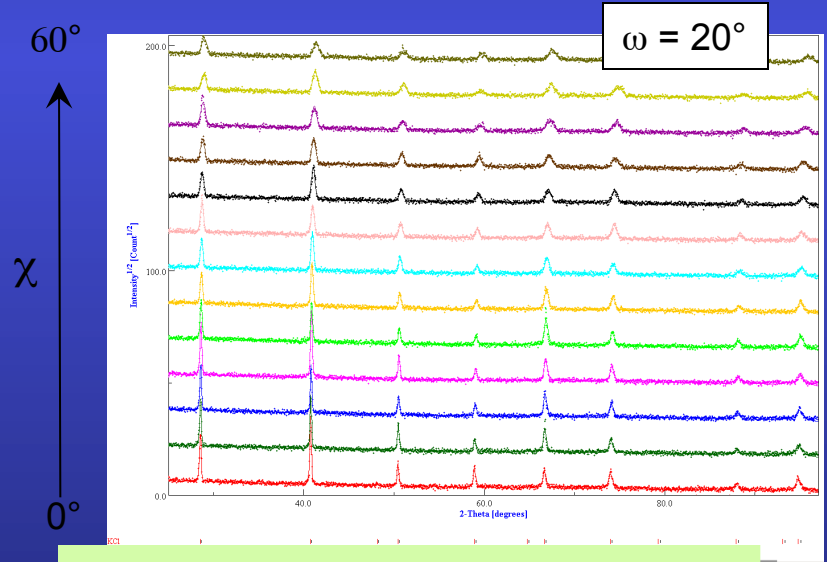
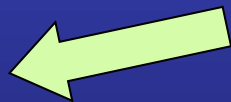
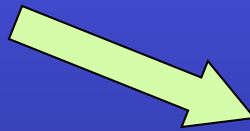
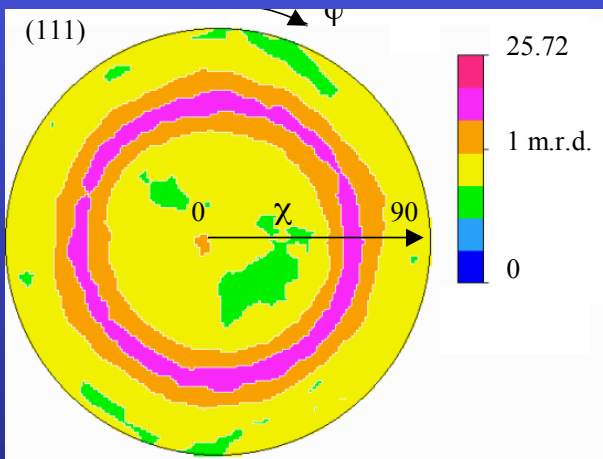
Ferroelectric PCT films

J. Ricote, Madrid

thin films:

$(\text{Ca}_{0.24}\text{Pb}_{0.76})\text{TiO}_3$ sol-gel synthesised solutions deposited by spin coating on a substrate of $\text{Pt}/\text{TiO}_2/\text{Si}$, with and without a treatment at 650°C for 30 min.

All films are crystallised at 700°C for 50 s by Rapid Thermal Processing (RTP; $30^\circ\text{C}/\text{s}$). A series is also recrystallised at 650°C for 1 to 3 h.



Refinement of individual spectra

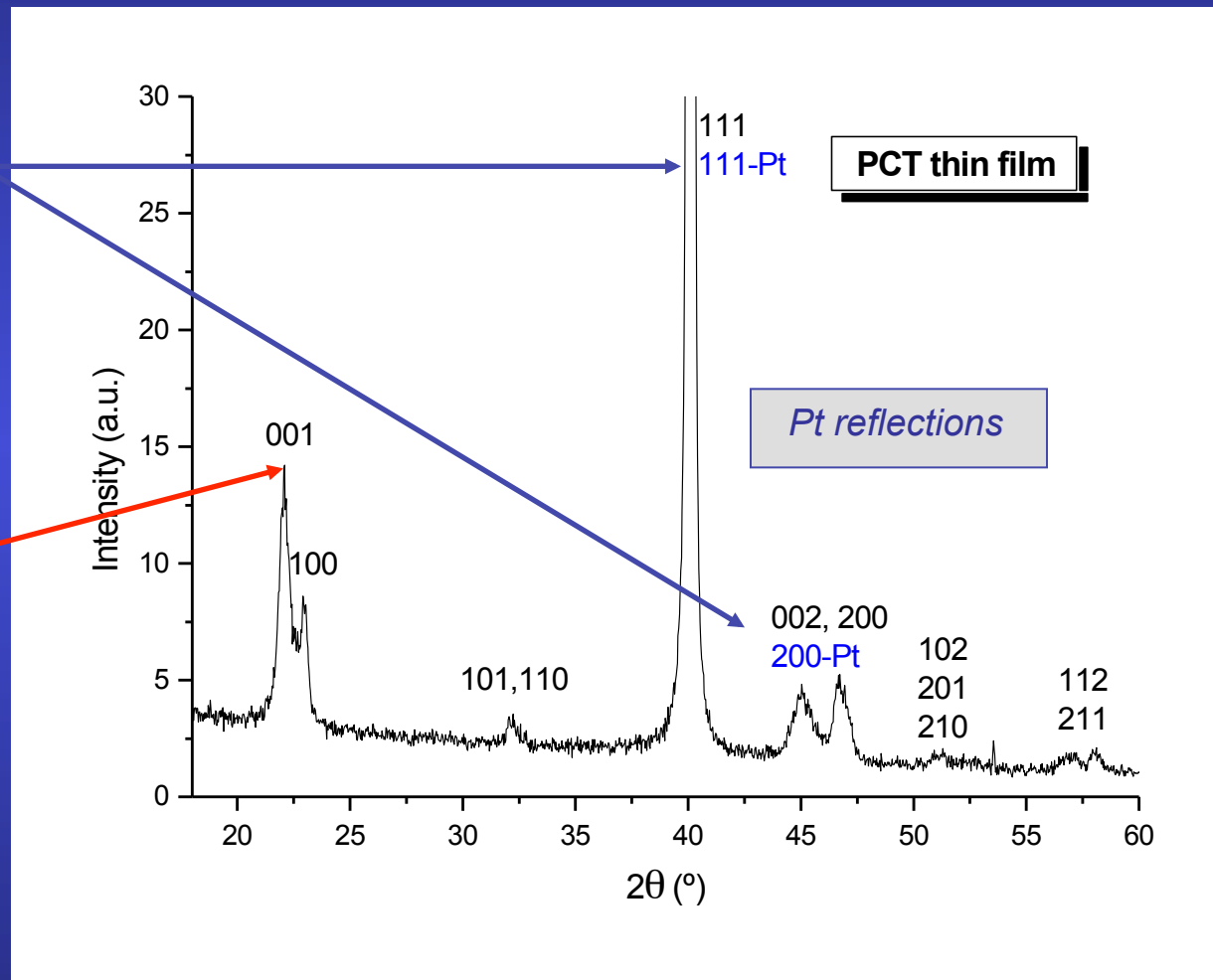
Limitations of the simple Quantitative Texture Analysis

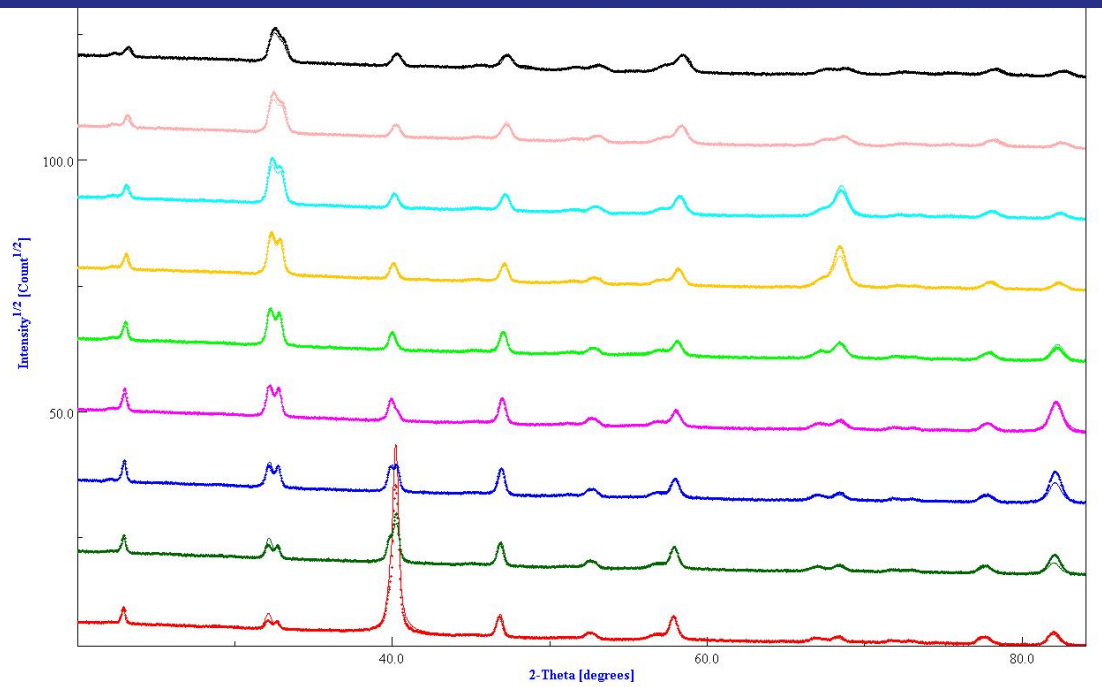
Structural parameters are difficult to obtain due to:

Substrate influence:

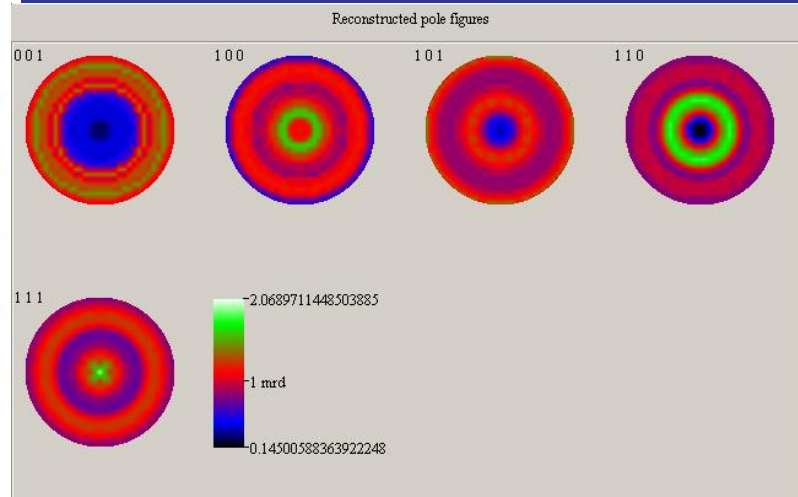
overlapping of reflections from the film and the substrate

TEXTURE effects:
peaks that do not appear at low χ angles

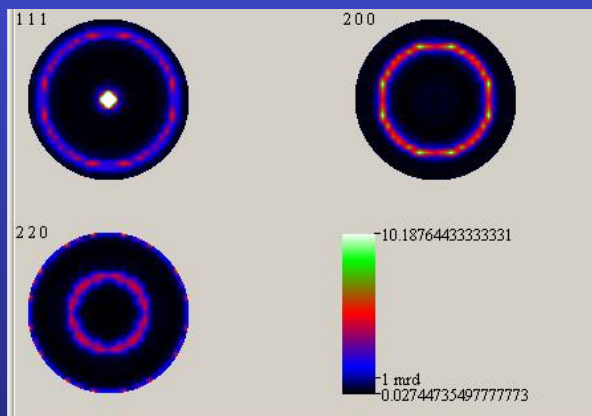




PCT



Pt



$a = 3.9108(1) \text{ \AA}$
 $T = 457(3) \text{ \AA}$
 $t_{\text{iso}} = 458(3) \text{ \AA}$
 $\epsilon' = 0.0032(1) \text{ rms}$

$a = 3.9156(1) \text{ \AA}$
 $c = 4.0497(3) \text{ \AA}$
 $T = 2525(13) \text{ \AA}$
 $t_{\text{iso}} = 390(7) \text{ \AA}$
 $\epsilon = 0.0067(1) \text{ rms}$

$R_W = 13\%$; $R_B = 12\%$; $R_{\text{exp}} = 22\%$.(Rietveld)
 $R_W = 5\%$; $R_B = 6\%$ (E-WIMV)

Structural parameters

Pt layer

| | a (Å) | thickness (nm) | R factors (%) |
|-----------------------|-----------|----------------|------------------------------|
| non-treated substrate | | | |
| Pt | 3.9108(1) | 45.7(3) | $R_W=13, R_B=12, R_{exp}=22$ |
| annealed substrate | | | |
| Pt | 3.9100(4) | 46.4(3) | $R_W=8, R_B=14, R_{exp}=21$ |
| Pt (Recryst. 1h) | 3.9114(2) | 47.8(3) | $R_W=9, R_B=20, R_{exp}=21$ |
| Pt (Recryst. 2h) | 3.9068(1) | 46.9(3) | $R_W=9, R_B=14, R_{exp}=22$ |
| Pt (Recryst. 3h) | 3.9141(4) | 47.5(9) | $R_W=27, R_B=12, R_{exp}=21$ |

Annealing of the substrate does not introduce significant variations on the structure of the Pt layer

PTC film

| | a (Å) | c (Å) | thickness (nm) |
|--------------------------|-----------|------------|----------------|
| on non-treated substrate | | | |
| PCT | 3.9156(1) | 4.0497(6) | 272.5(13) |
| on annealed substrate | | | |
| PCT | 3.8920(6) | 4.0187(8) | 279.0(9) |
| PCT (Recryst. 1h) | 3.8929(2) | 4.0230(4) | 266.1(11) |
| PCT (Recryst. 2h) | 3.8982(2) | 4.0227(4) | 258.4(9) |
| PCT (Recryst. 3h) | 3.9001(4) | 4.0228(11) | 253.6(29) |

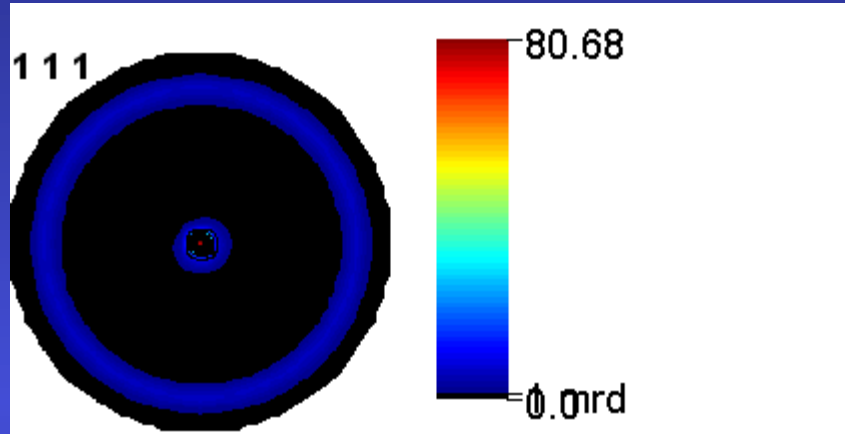
Recrystallisation reduces the stress on the film, and, increases the lattice parameters

| Compliance coefficients [10 ⁻³ GPa ⁻¹] | PbTiO ₃ single crystal (data set A) | Film random orientation | PCT-Si <001> contrib.≈17% | PLT <001> contrib.≈49% | PCT-Mg <001> contrib.≈68% |
|--|--|-------------------------------|---------------------------------|------------------------------|---------------------------------|
| S ₁₁ | 6.5 | 10.1 | 10.5 | 10.0 | 9.7 |
| S ₂₂ | 6.5 | 10.0 | 10.5 | 10.0 | 9.7 |
| S ₃₃ | 33.3 | 9.8 | 9.0 | 10.3 | 11.3 |
| S ₄₄ | 14.5 | 13.2 | 12.8 | 12.9 | 13.1 |
| S ₅₅ | 14.5 | 13.2 | 12.8 | 13.0 | 13.1 |
| S ₆₆ | 9.6 | 13.4 | 14.0 | 13.5 | 12.7 |
| S ₁₂ | -0.35 | -3.3 | -3.5 | -3.2 | -3.0 |
| S ₂₁ | -0.35 | -3.3 | -3.5 | -3.2 | -3.0 |
| S ₁₃ | -7.1 | -3.2 | -3.1 | -3.4 | -3.6 |
| S ₃₁ | -7.1 | -3.2 | -3.1 | -3.4 | -3.6 |
| S ₂₃ | -7.1 | -3.2 | -3.1 | -3.4 | -3.6 |
| S ₃₂ | -7.1 | -3.2 | -3.1 | -3.4 | -3.6 |
| S ₃₃ /S ₁₁ | 5.1 | 0.97 | 0.86 | 1.03 | 1.16 |
| S ₁₃ /S ₁₂ | 20.3 | 0.97 | 0.89 | 1.06 | 1.20 |

Geometric mean average + biaxial stress state

Ferroelectric PMN-PT films

J. Ricote, DMF-Madrid



Pt

$$a = 3.91172(1) \text{ \AA}$$

$$T = 583(5) \text{ \AA}$$

$$t_{\text{iso}} = 960(1) \text{ \AA}$$

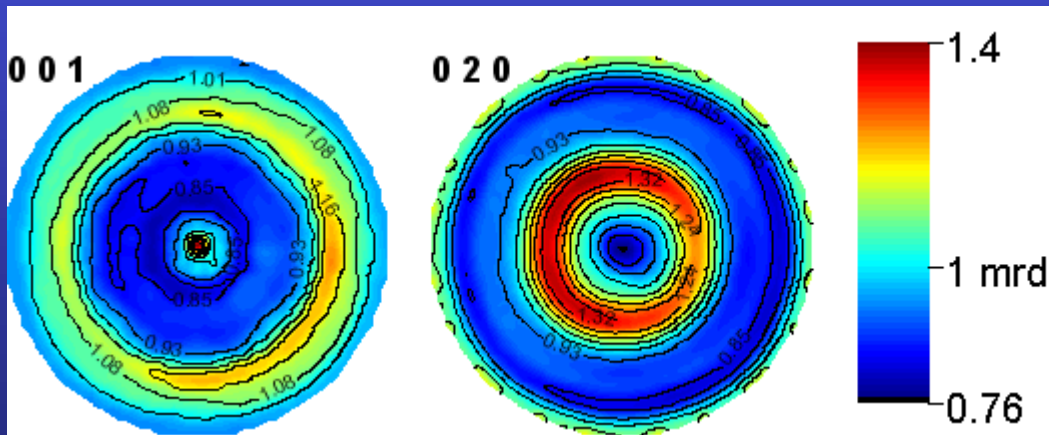
$$\varepsilon = 0.0032(1) \text{ rms}$$

$$\sigma_{11} = 0.639(1) \text{ GPa}$$

$$\sigma_{22} = 0.651(1) \text{ GPa}$$

$$\sigma_{12} = -0.009(1) \text{ GPa}$$

$\text{Pb}_{0.7}(\text{Mg}_{1/3}\text{Nb}_{2/3})\text{O}_3\text{-Pb}_{0.3}\text{TiO}_3 / \text{TiO}_2 / \text{Pt} / \text{Si}(100)$



$$a = 5.67858(9) \text{ \AA}$$

$$b = 5.69038(9) \text{ \AA}$$

$$c = 3.99558(4) \text{ \AA}$$

$$\beta = 90.392(1) \text{ \AA}$$

$$T = 1322(9) \text{ \AA}$$

$$t_{\text{iso}} = 1338(2) \text{ \AA}$$

$$\varepsilon = 0.0067(1) \text{ rms}$$

Si nanocrystalline thin films

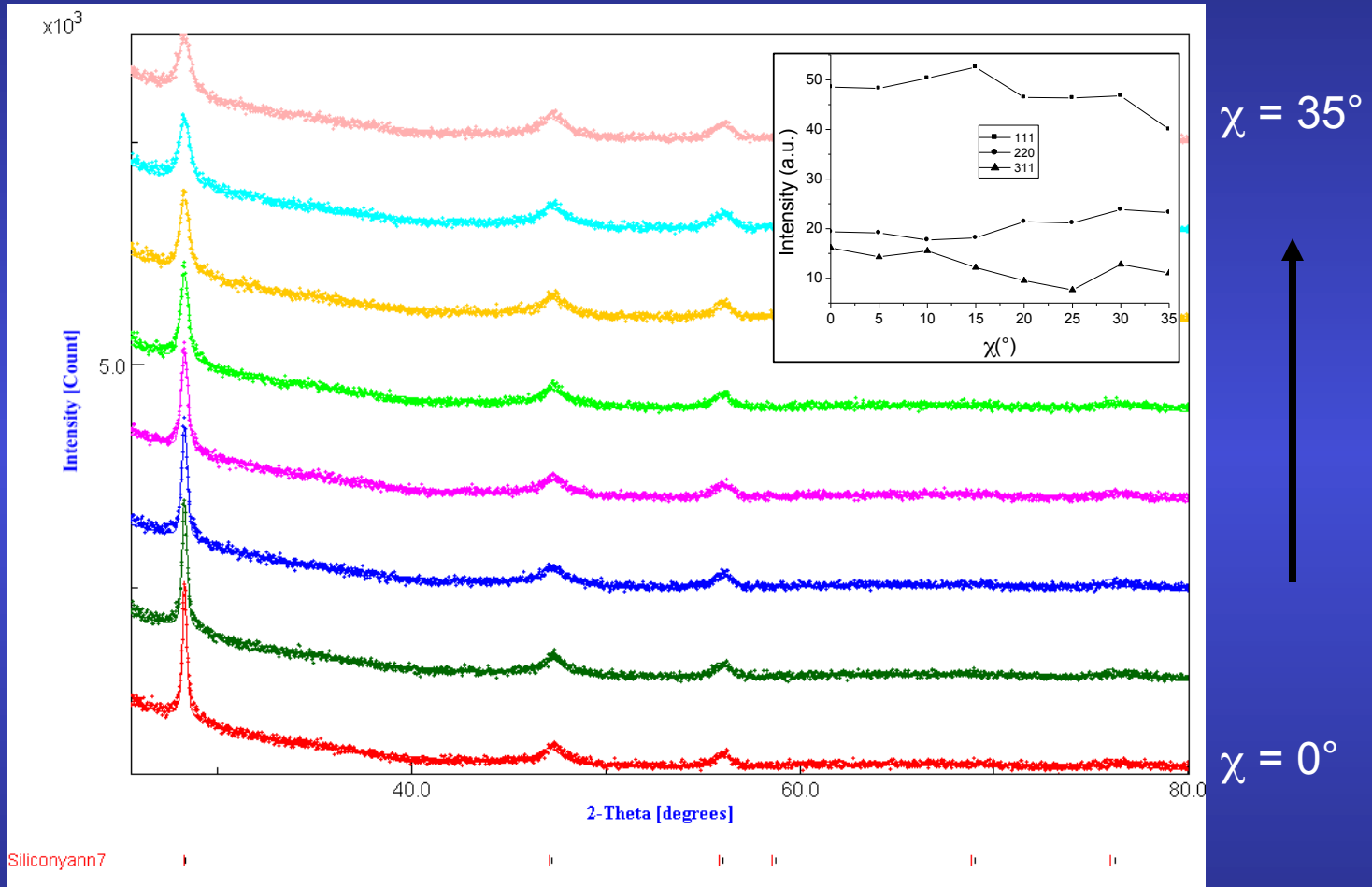
M. Morales, Caen

Silicon thin films deposition by reactive magnetron sputtering:

- ⇒ power density $2\text{W}/\text{cm}^2$
- ⇒ total pressure: $p_{\text{total}} = 10^{-1}$ Torr
- ⇒ plasma mixture: H_2 / Ar , $p_{\text{H}_2} / p_{\text{total}} = 80\%$
- ⇒ temperature: 200°C
- ⇒ substrates: amorphous SiO_2 (a- SiO_2)
(100)-Si single-crystals
- ⇒ target-substrate distance (d)
 - a- SiO_2 substrates: $d = 4, 6, 7, 8, 10, 12$ cm
films A, B, C, D, E, F
 - (100)-Si: $d = 6, 12$ cm
films G, H

Aim: quantum confinement, photoluminescence properties

Typical refinement

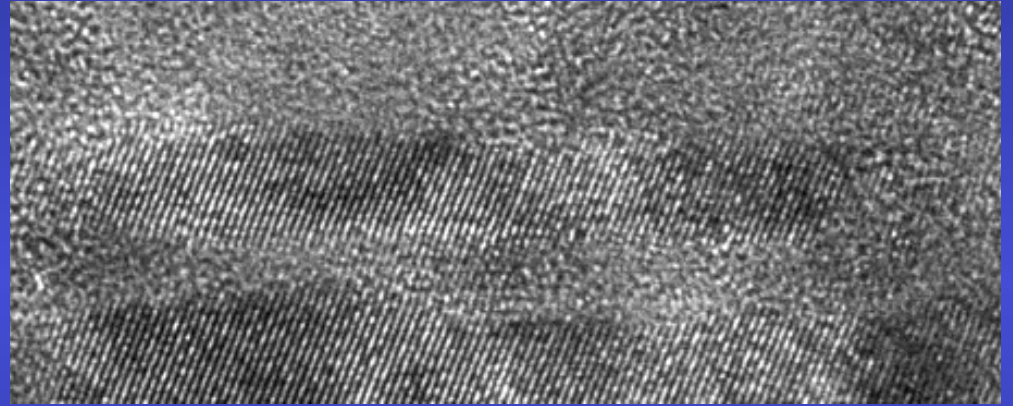
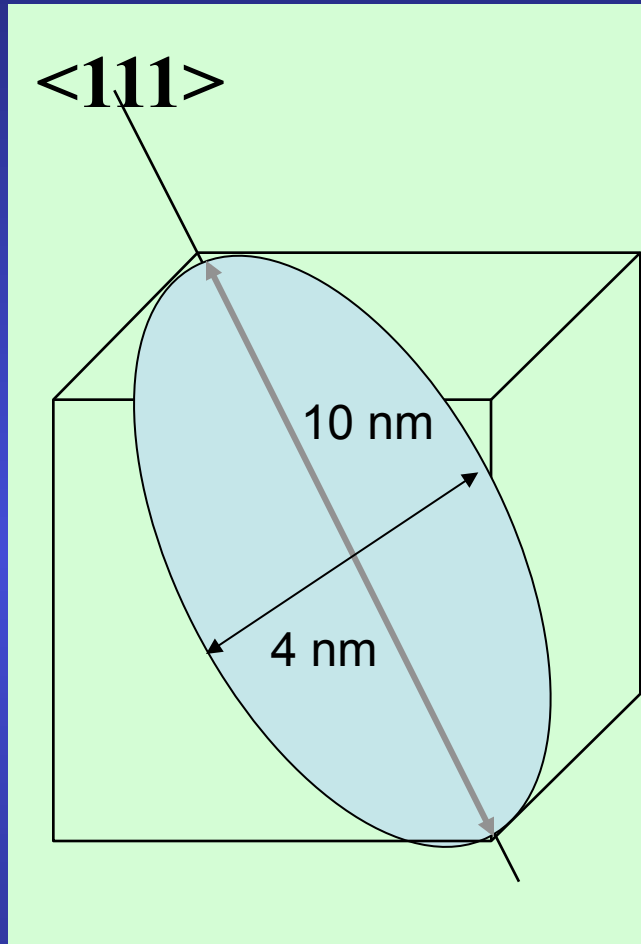


broad, anisotropic diffracted lines, textured samples

Refinement Results

| Sample | d (cm) | a (Å) | RX thickness (nm) | Anisotropic sizes (Å) | | | Texture parameters | | | Reliability factors (%) | | | |
|--------|--------|------------|-------------------------|-----------------------|-------|-------|---------------------|---------------------|---|-------------------------|----------------|----------------|------------------|
| | | | | <111> | <220> | <311> | Maximum (m.r.d.) | minimum (m.r.d.) | Texture index F ² (m.r.d ²) | RP ₀ | R _w | R _B | R _{exp} |
| A | 4 | 5.4466 (3) | — | 94 | 20 | 27 | 1.95 | 0.4 | 1.12 | 1.72 | 4.0 | 3.7 | 3.5 |
| B | 6 | 5.4439 (2) | 711 (50) | 101 | 20 | 22 | 1.39 | 0.79 | 1.01 | 0.71 | 4.9 | 4.3 | 4.2 |
| C | 7 | 5.4346 (4) | 519 (60) | 99 | 40 | 52 | 1.72 | 0.66 | 1.05 | 0.78 | 4.3 | 4.0 | 3.9 |
| D | 8 | 5.4461 (2) | 1447 (66) | 100 | 22 | 33 | 1.57 | 0.63 | 1.04 | 0.90 | 5.5 | 4.6 | 4.5 |
| E | 10 | 5.4462 (2) | 1360 (80) | 98 | 20 | 25 | 1.22 | 0.82 | 1.01 | 0.56 | 5.0 | 3.9 | 4.0 |
| F | 12 | 5.4452 (3) | 1110 (57) | 85 | 22 | 26 | 1.59 | 0.45 | 1.05 | 1.08 | 4.2 | 3.5 | 3.7 |
| G | 6 | 5.4387 (3) | 1307 (50) | 89 | 22 | 28 | 1.84 | 0.71 | 1.01 | 1.57 | 5.2 | 4.7 | 4.2 |
| H | 12 | 5.4434 (2) | 1214 (18) | 88 | 22 | 24 | 2.77 | 0.50 | 1.12 | 2.97 | 5.0 | 4.5 | 4.3 |

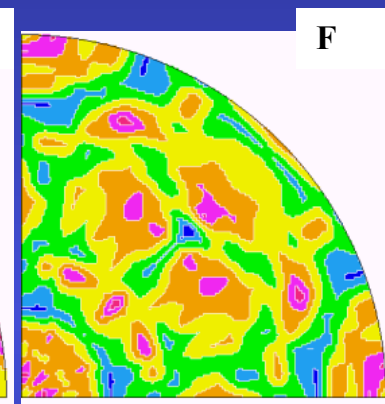
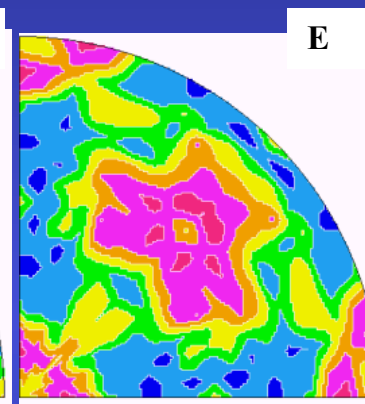
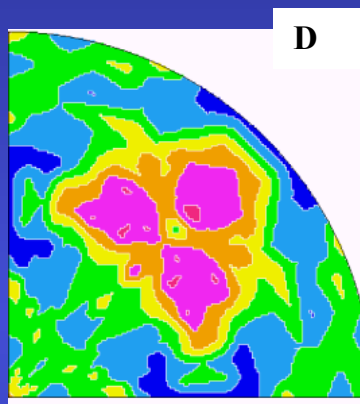
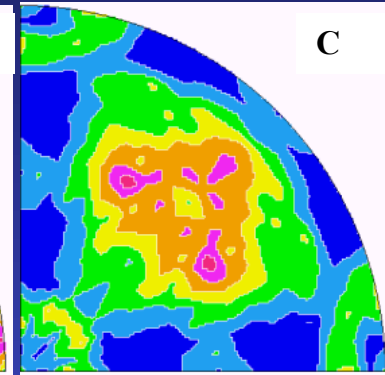
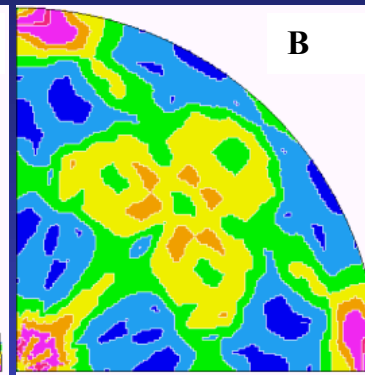
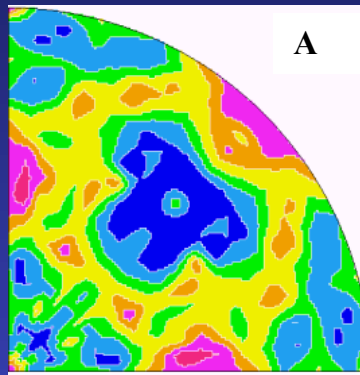
Mean anisotropic shape



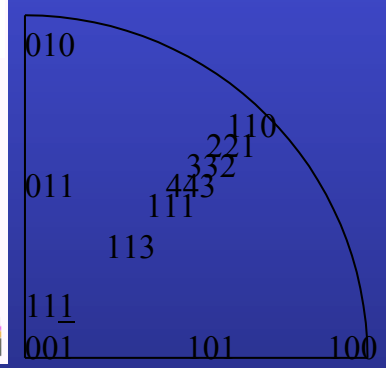
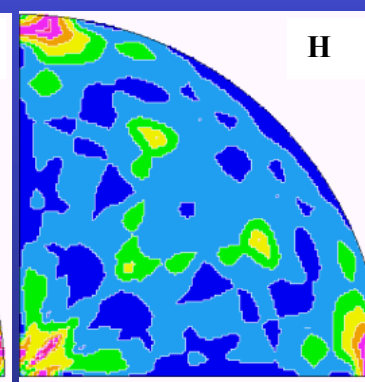
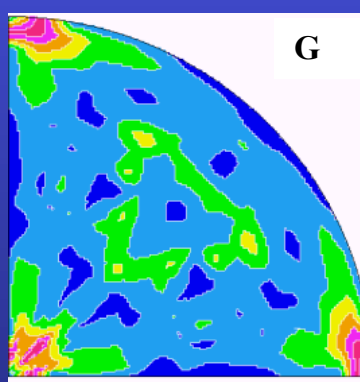
Schematic of the mean crystallite shape for Sample D represented in a cubic cell, as refined using the Popa approach and exhibiting a strong elongation along $\langle 111 \rangle$, and TEM image

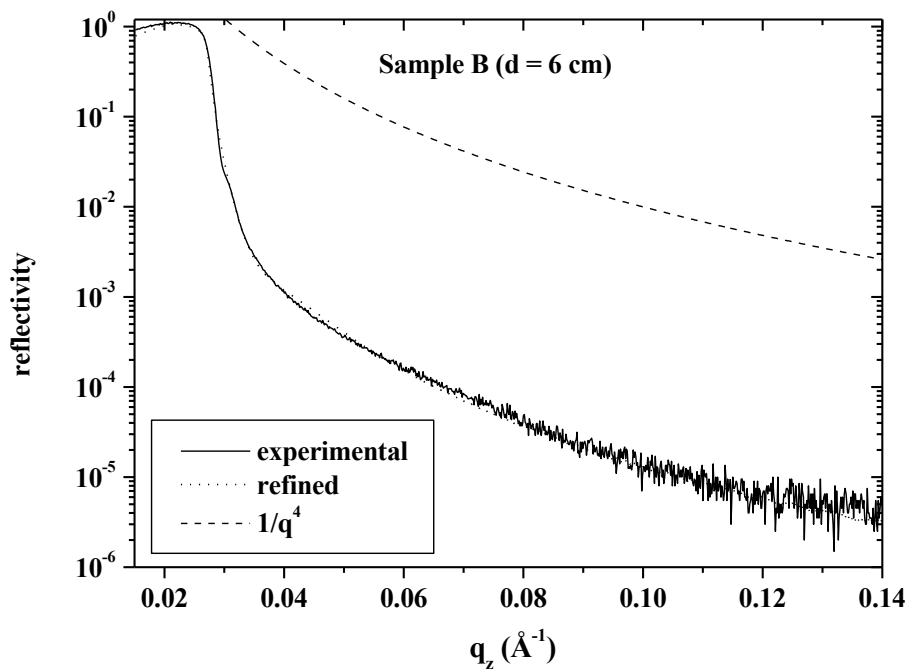
001 Inverse Pole Figures

a-SiO₂



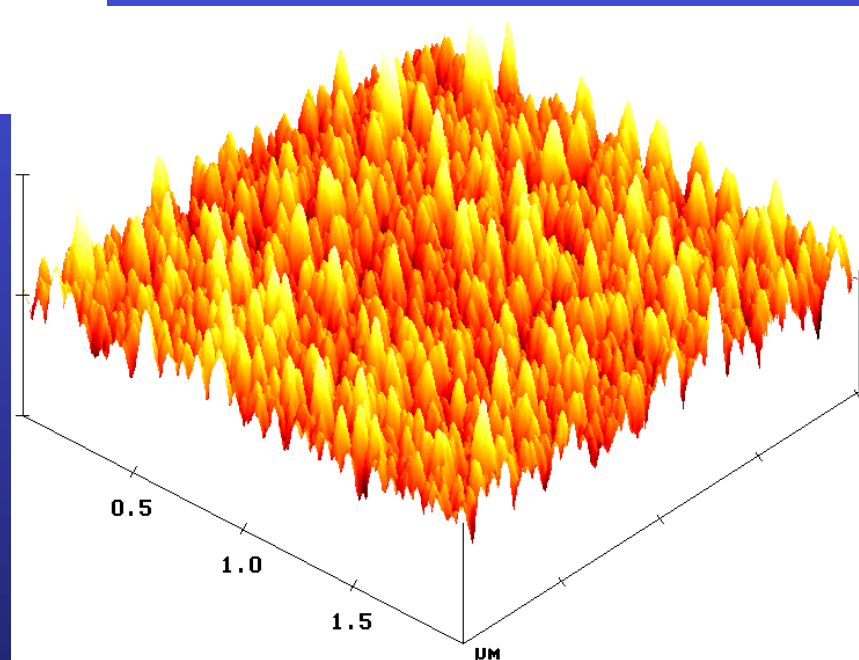
(100)-Si

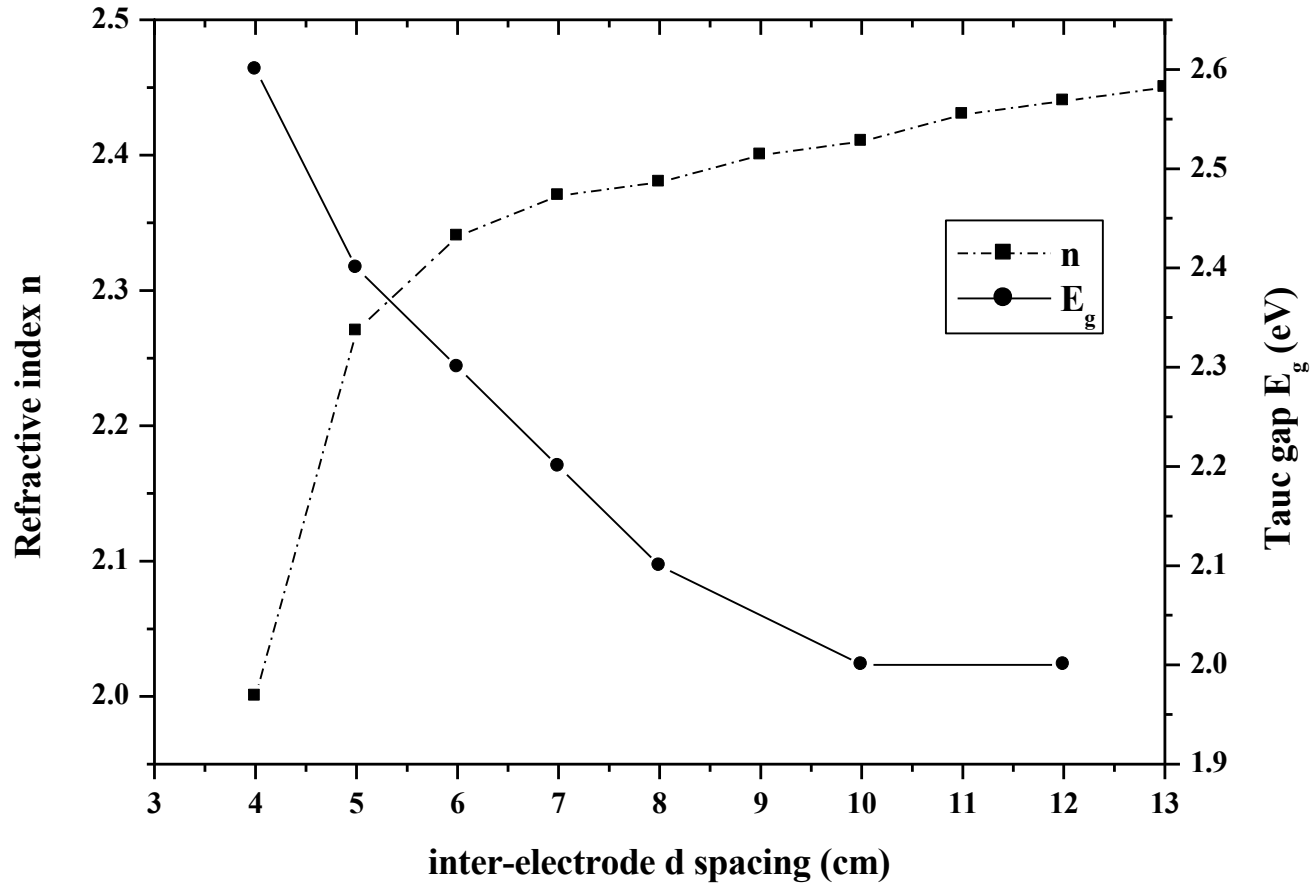




XRR:
Roughness
governed

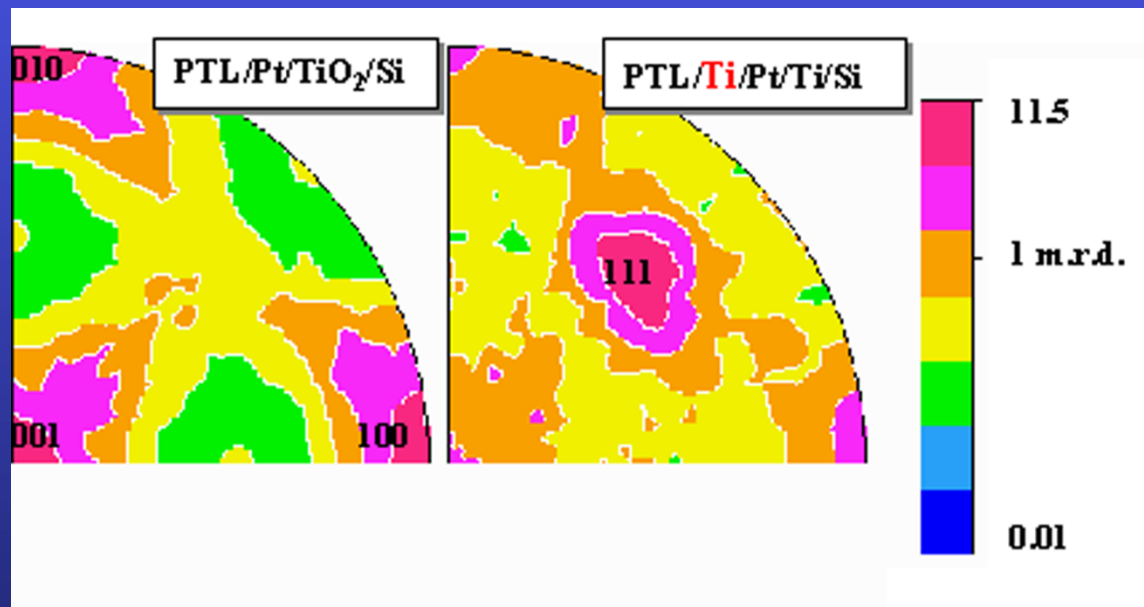
AFM:
homogeneous
roughness





↪ Refractive index linked to film porosities:
 Larger target-sample distances: increased compacity due to lower
 nanopowder filling

| Atom | Occupancy | x | y | z |
|------|-----------|-----|-----|----------|
| Pb | 0.76 | 0.0 | 0.0 | 0.0 |
| Ca | 0.24 | 0.0 | 0.0 | 0.0 |
| Ti | 1.0 | 0.5 | 0.5 | 0.477(2) |
| O1 | 1.0 | 0.5 | 0.5 | 0.060(2) |
| O2 | 1.0 | 0.0 | 0.5 | 0.631(1) |

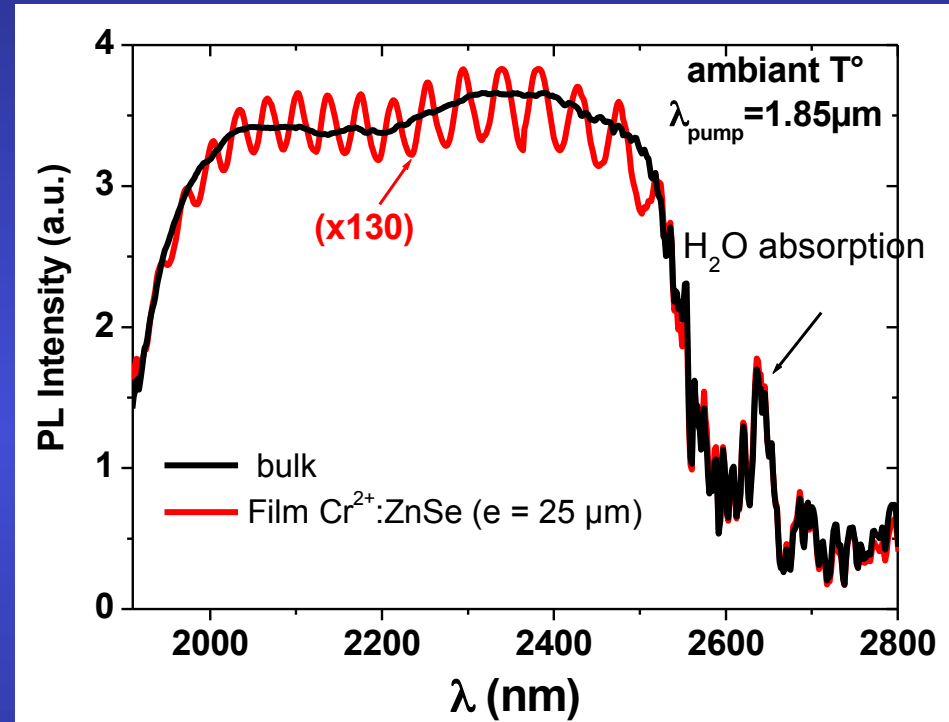
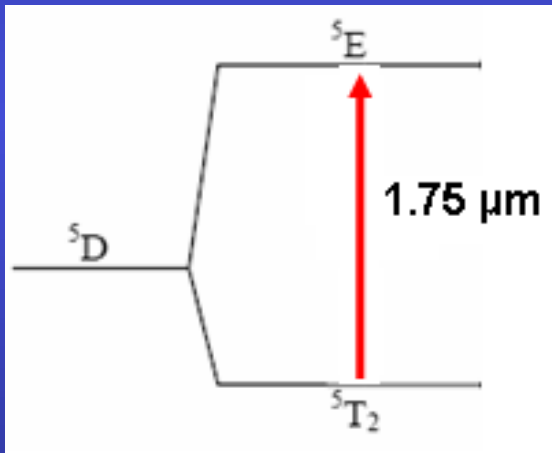


ZnSe:Cr²⁺ films

M. Morales

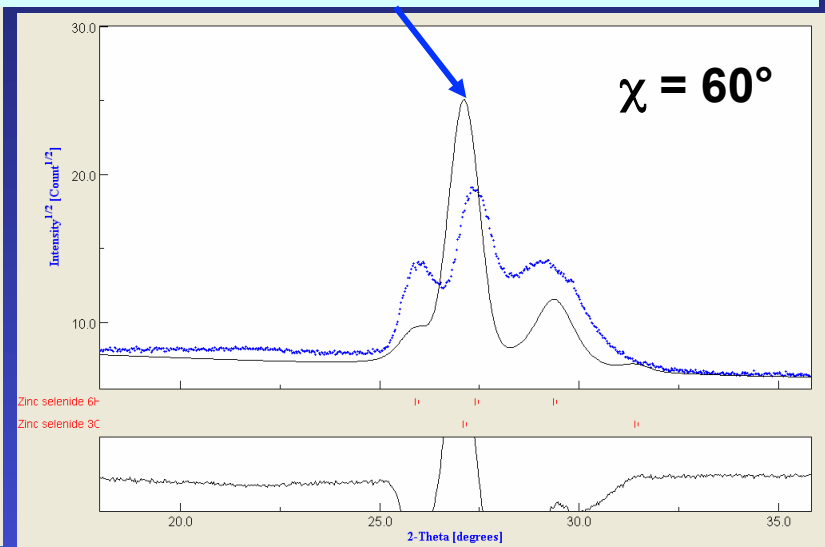
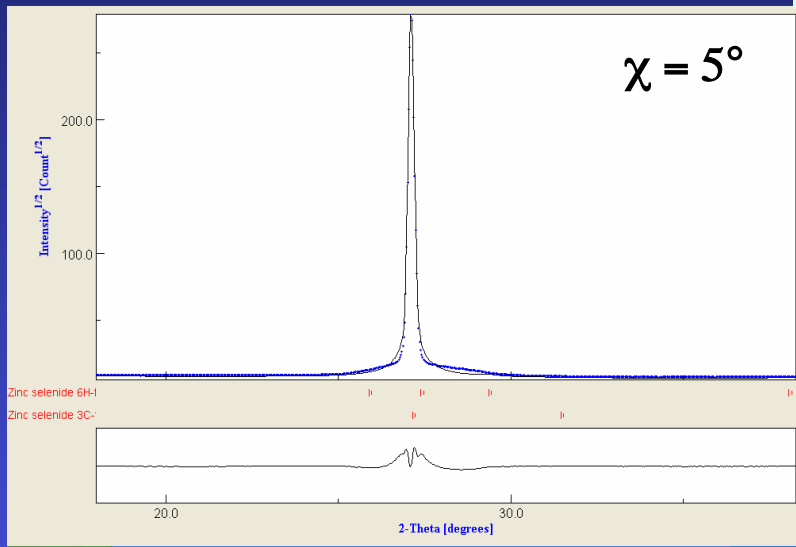
conditions:

- ◆ $20 \leq T_d \leq 385^\circ\text{C}$
- ◆ $P_{\text{RF}} = 50\text{-}200\text{W}$
- ◆ $P_{\text{Ar}} = 0.5\text{ Pa and } 2\text{ Pa}$
- ◆ $d = 7\text{ and } 10\text{ cm}$

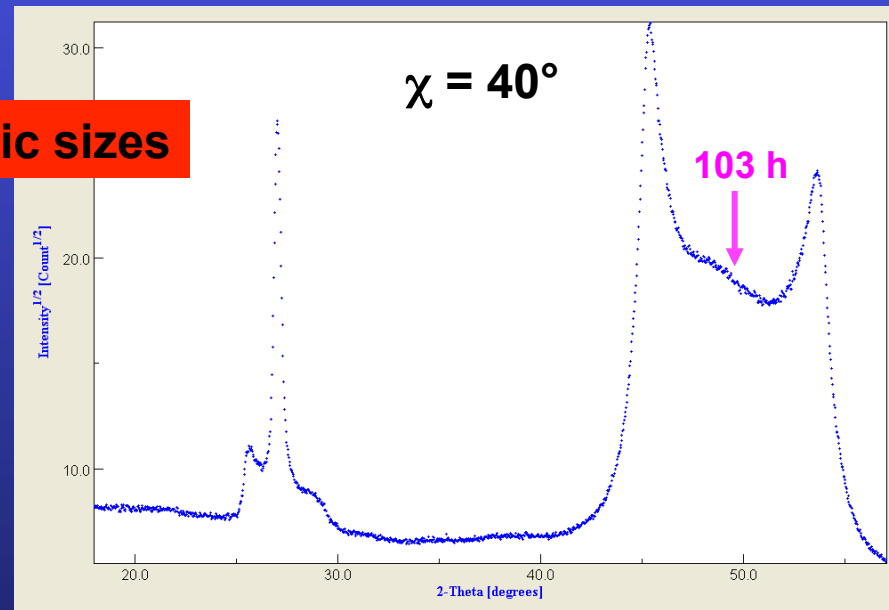
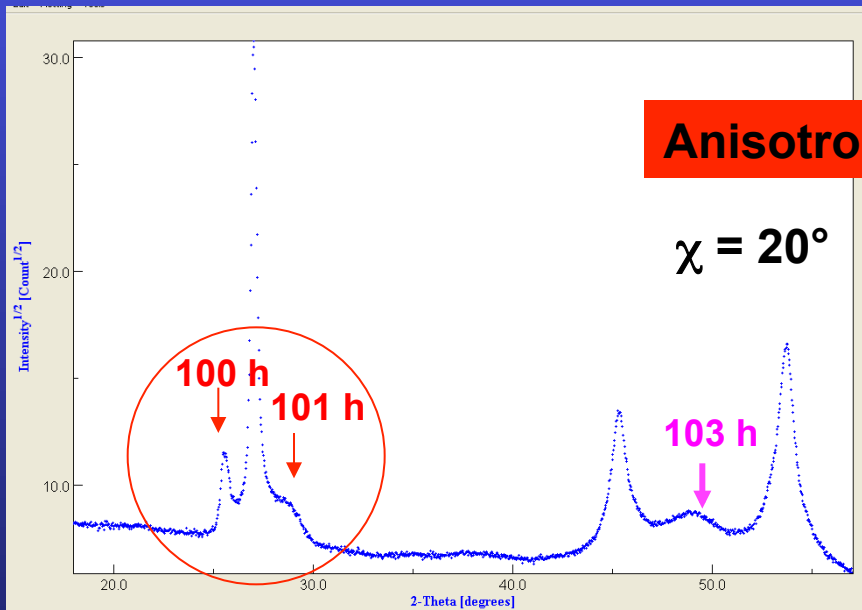


- ◆ Large emission band centred at 2200nm: $^5E \rightarrow ^5T_2$ transition (Cr^{2+})
- ◆ Single crystals and thin films: similar spectra

111 Peak shifts

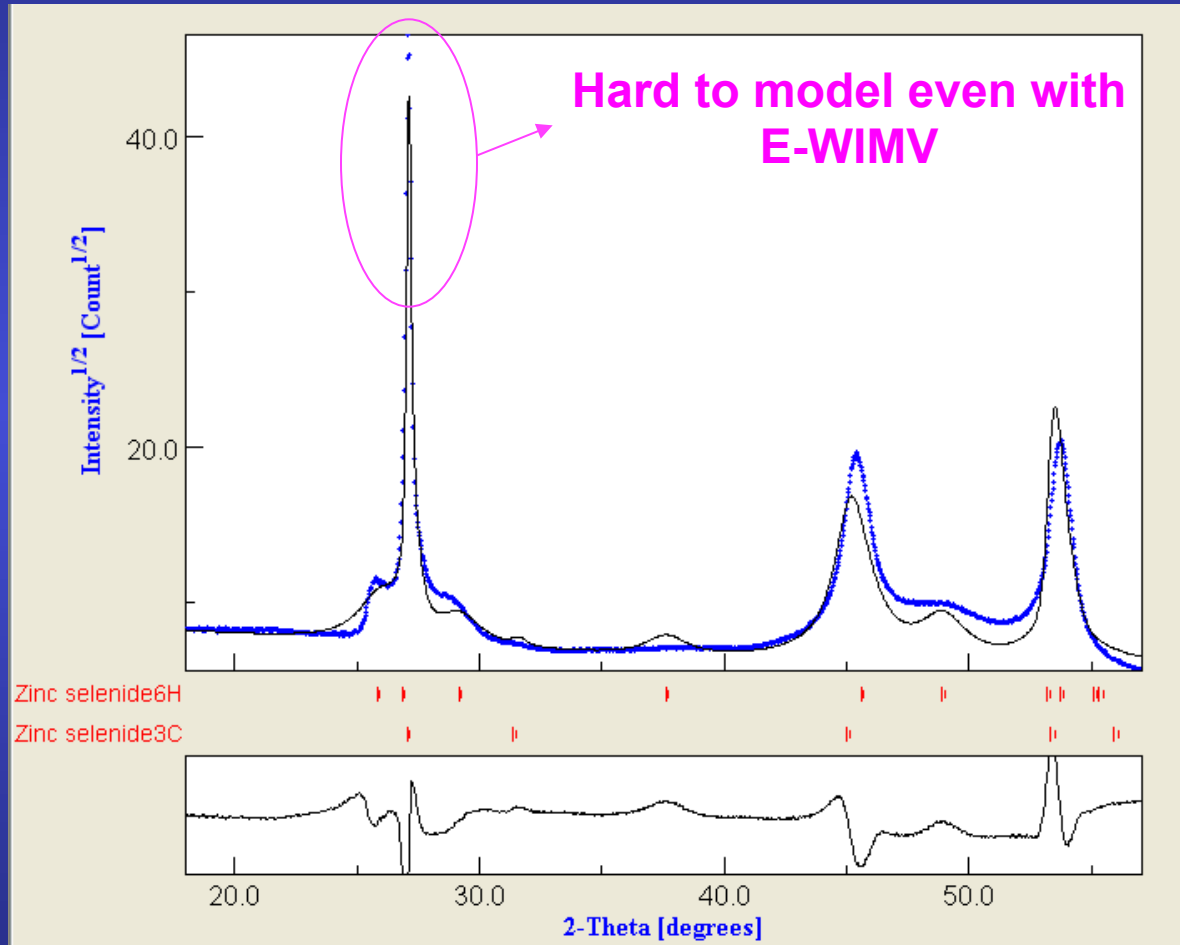


Residual stresses and/or stacking faults



Anisotropic sizes

Fibre Texture + 2 polytypes (6H and 3C) + anisotropic sizes + residual stresses and/or stacking faults + layering

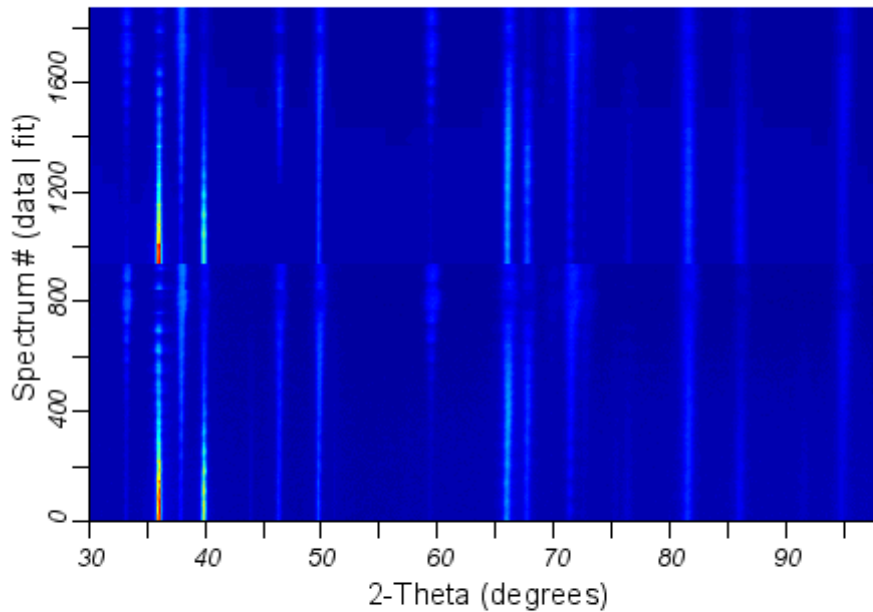


Sum diagram: $\omega = 13.65^\circ$, $P_{RF} = 200W$

AIN/Pt/TiO_x/Al₂O₃/Ni-Co-Cr-Al

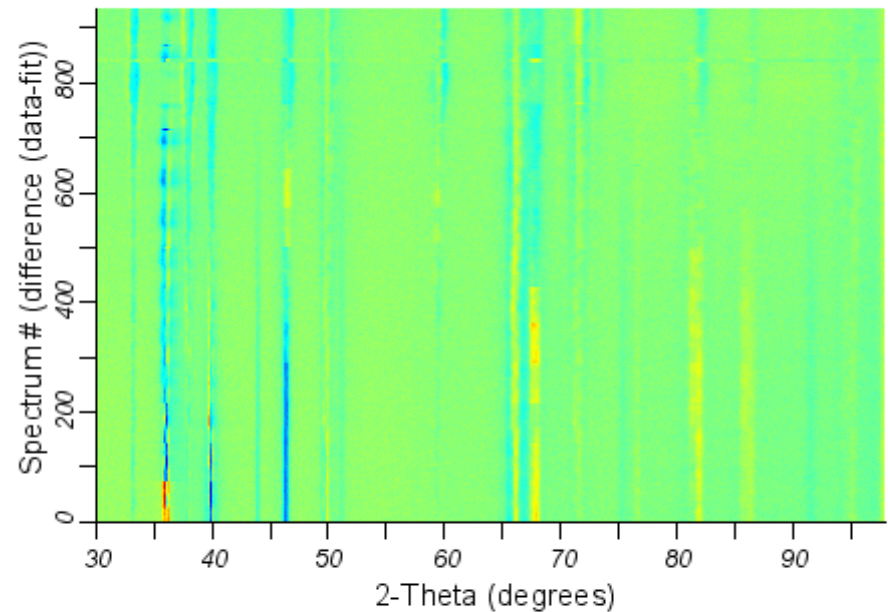
2D Multiplot for Data 05_37P64

measured data and fit



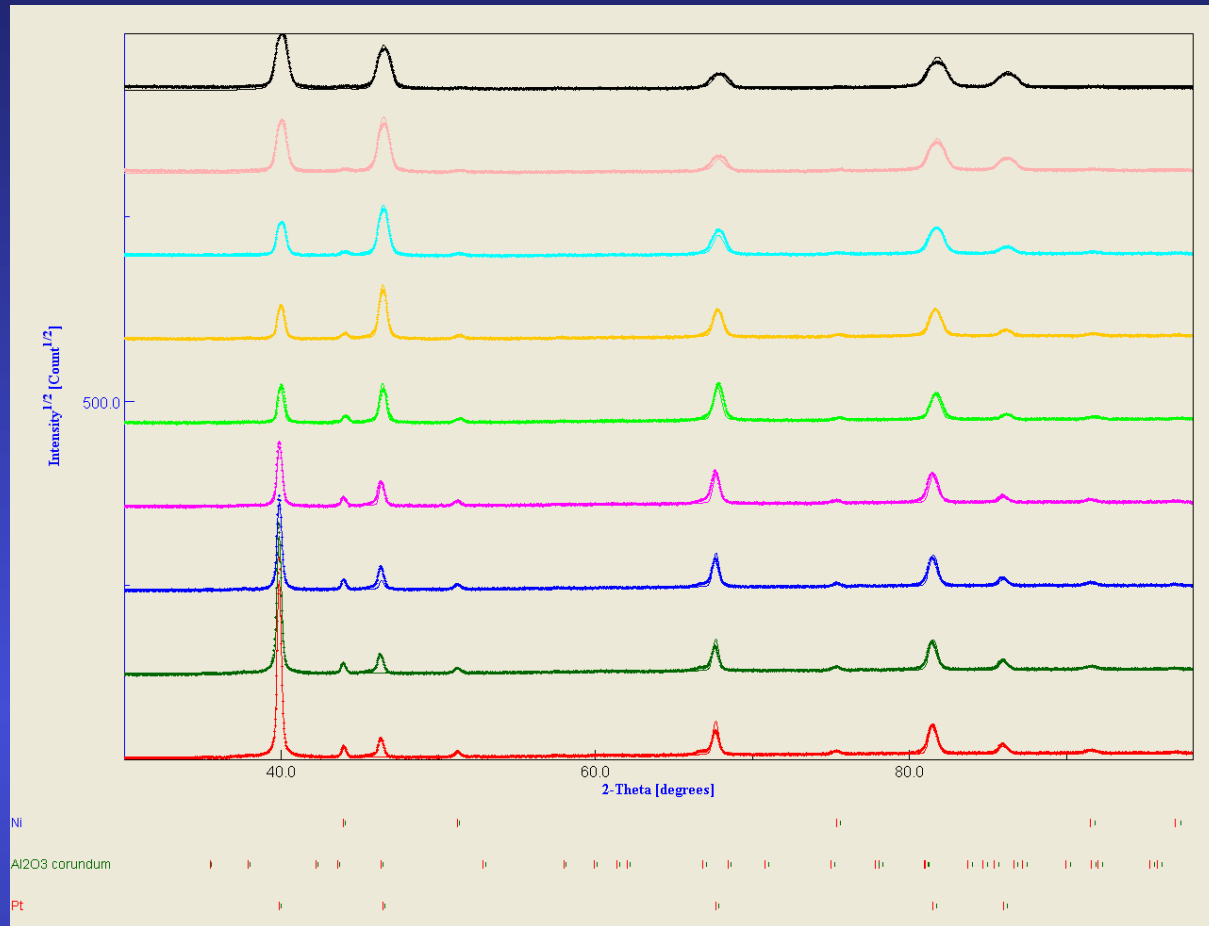
2D difference plot for Data 05_37P64

difference data - fit



Rw (%) = 24.120445
Rexp (%) = 5.8517213

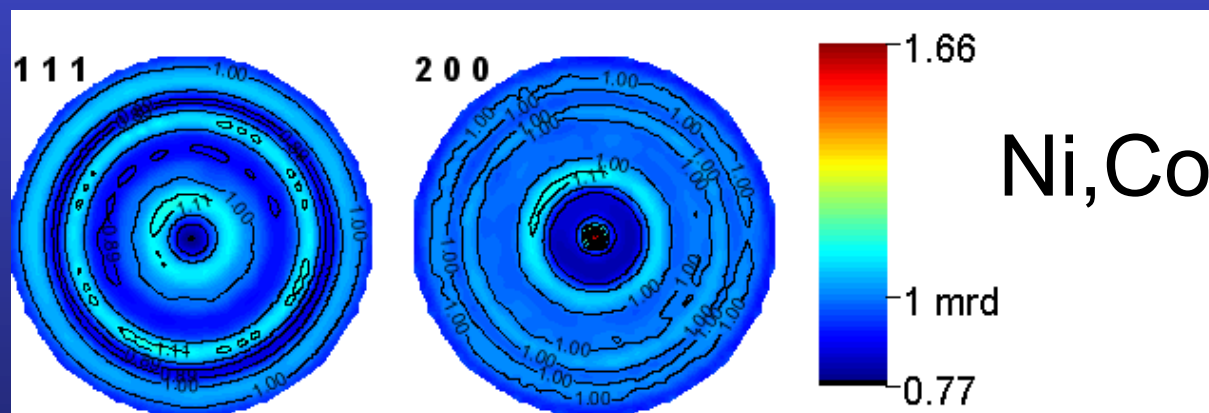
T(AIN) = 14270(3) nm
T(Pt) = 430(3) nm



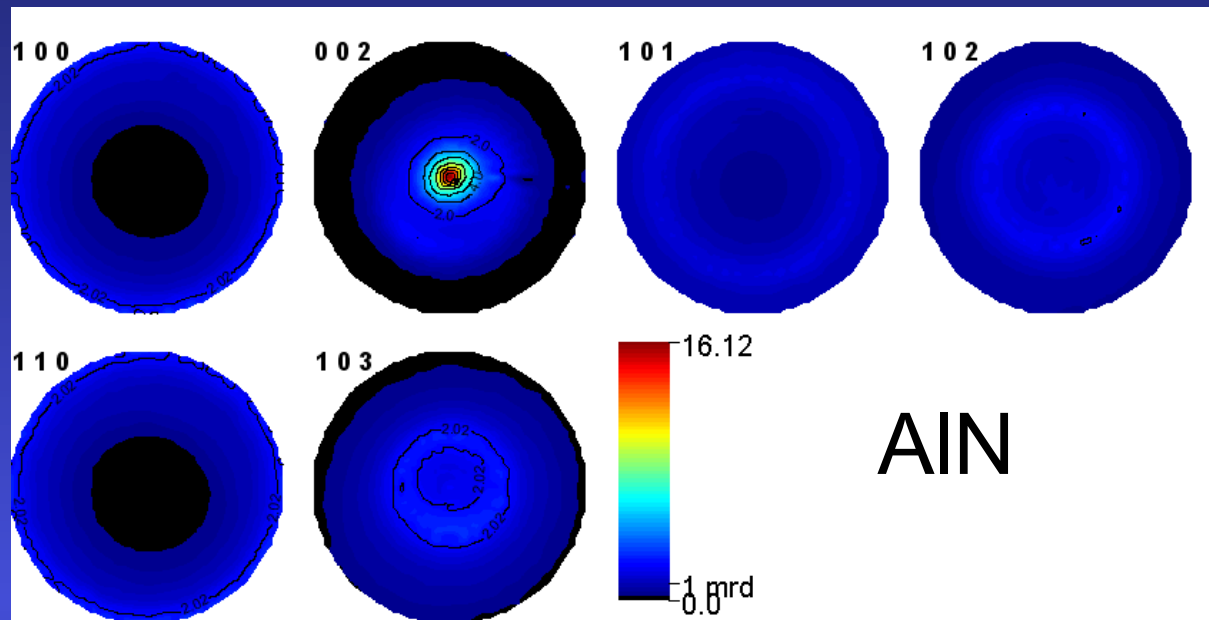
(χ, φ) randomly
selected diagrams



$a = 4.7562(6) \text{ \AA}$
 $c = 12.875(3) \text{ \AA}$
 $T = 7790(31) \text{ nm}$
 $\langle t \rangle = 150(2) \text{ \AA}$
 $\langle \varepsilon \rangle = 0.008(3)$



$a = 3.569377(5) \text{ \AA}$
 $\langle t \rangle = 7600(1900) \text{ \AA}$
 $\langle \varepsilon \rangle = 0.00236(3)$
 $\sigma_{11} = -328(8) \text{ MPa}$
 $\sigma_{22} = -411(9) \text{ MPa}$



Rw (%) = 4.1

$a = 3.11203(1) \text{ \AA}$

$c = 4.98252(1) \text{ \AA}$

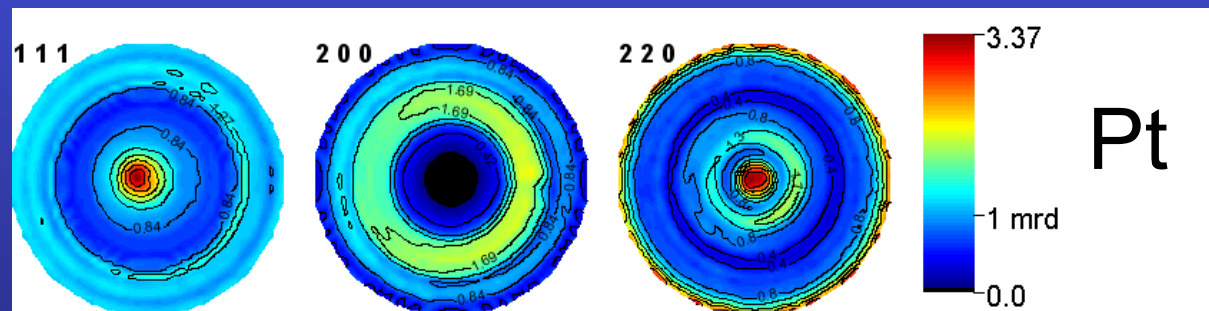
$T = 14270(3) \text{ nm}$

$\langle t \rangle = 2404(8) \text{ \AA}$

$\langle \varepsilon \rangle = 0.001853(2)$

$\sigma_{11} = -1019(2) \text{ MPa}$

$\sigma_{22} = -845(2) \text{ MPa}$



Rw (%) = 33.3

$a = 3.91198(1) \text{ \AA}$

$T = 1204(3) \text{ nm}$

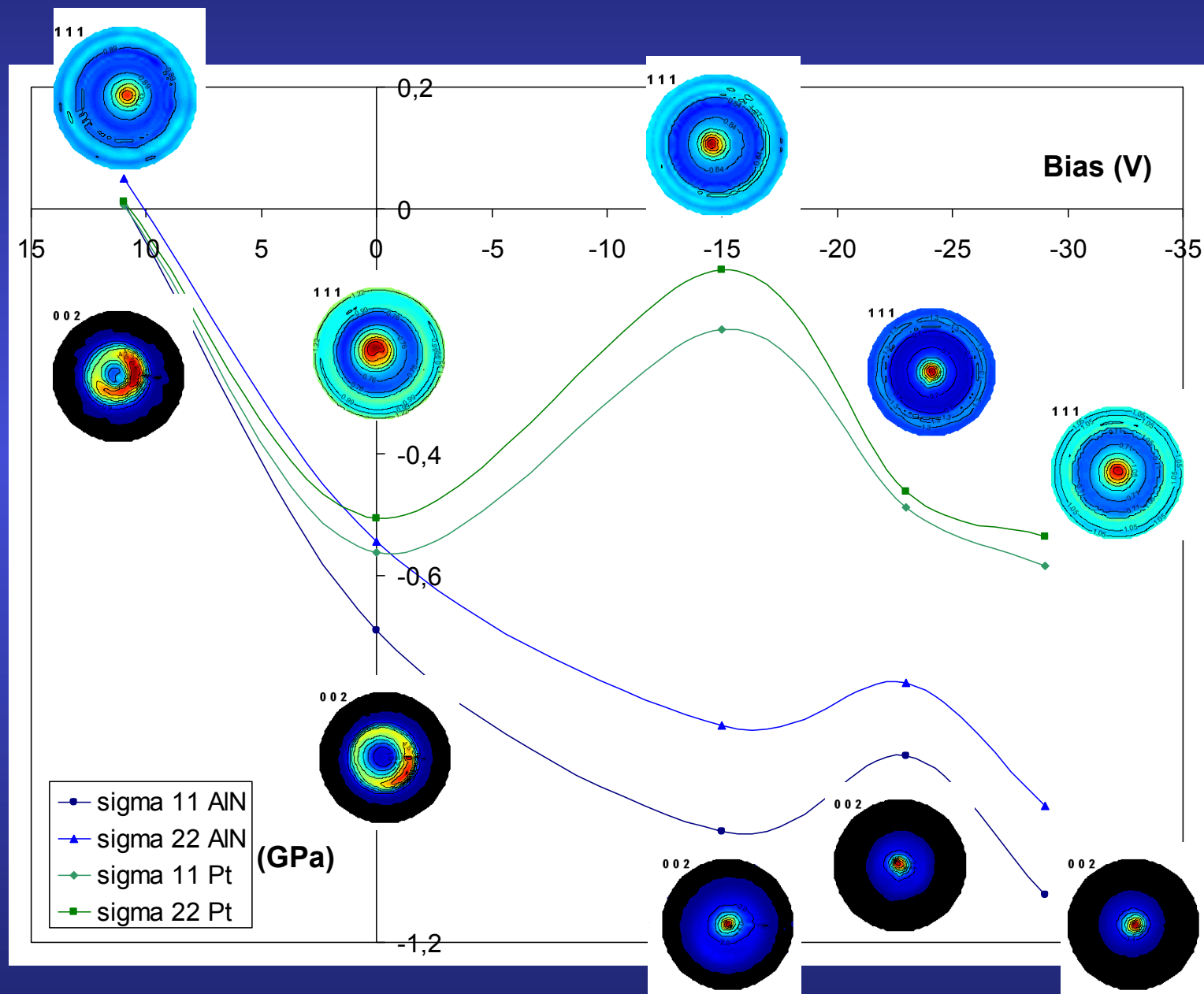
$\langle t \rangle = 2173(10) \text{ \AA}$

$\langle \varepsilon \rangle = 0.002410(3)$

$\sigma_{11} = -196.5(8)$

$\sigma_{22} = -99.6(6)$

Substrate bias vs stress-texture evolution



Independent measurements: why not more

Different wavelengths and rays: TEM, RHEED

Reflectivity: thickness, roughness, electron density profiles

X-ray Fluorescence: composition

Spectroscopies: local structures (PDF, FTIR, Mossbauer ...), eventually anisotropic (P-EXAFS, ESR, Raman ...), Element profiles (SIMS, RBS ...) ...

Physical models: magnetisation, conductivity ...

Environments: applied fields

Specular reflectivity: $\mathbf{q}=(0,0,z)$

- Fresnel:

$$R(\mathbf{q}) = \left| \frac{q_z - \sqrt{q_z^2 - q_c^2 + \frac{32i\pi^2\beta}{\lambda^2}}}{q_z + \sqrt{q_z^2 - q_c^2 + \frac{32i\pi^2\beta}{\lambda^2}}} \right|^2 \delta q_x \delta q_y$$

- matrix:

$$R^{flat} = \frac{r_{0,1}^2 + r_{1,2}^2 + 2r_{0,1}r_{1,2} \cos 2k_{z,1}h}{1 + r_{0,1}^2 r_{1,2}^2 + 2r_{0,1}r_{1,2} \cos 2k_{z,1}h}$$

- Born approximation:
Electron Density Profile

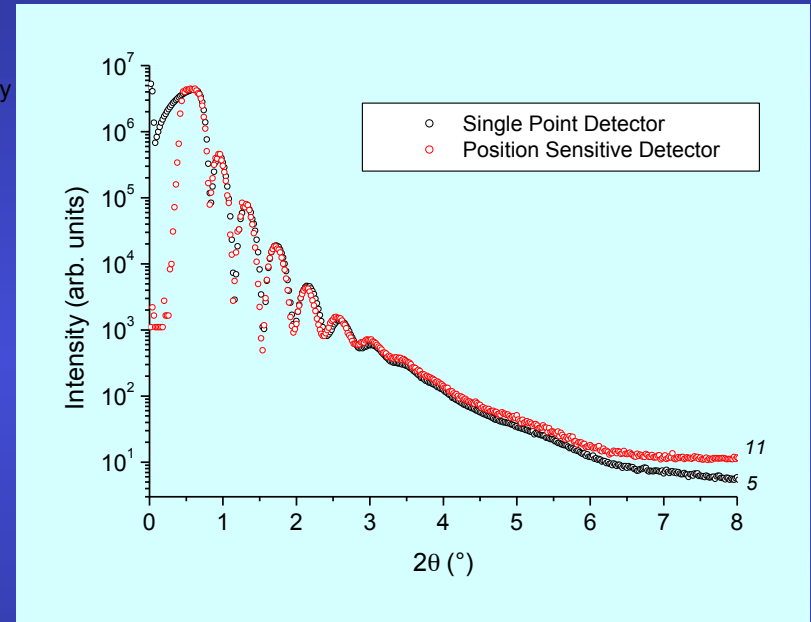
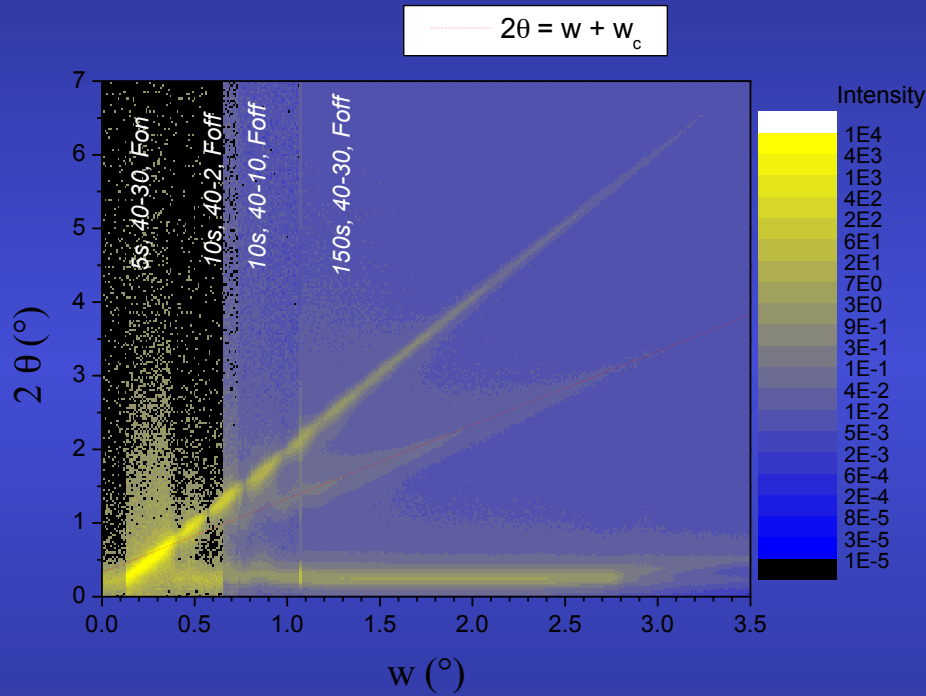
$$R(q_z) = r \cdot r^* = R_F(q_z) \left| \frac{1}{\rho_s} \int_{-\infty}^{+\infty} \frac{d\rho(z)}{dz} e^{iq_z z} dz \right|^2$$

- Roughness:

$$R^{rough}(q_z) = R(q_z) \exp(-q_{z,0} q_{z,1} \sigma^2) \quad \text{Low-angles (reflectivity)}$$

$$S_R = 1 - p \exp(-q) + p \exp\left(\frac{-q}{\sin \theta}\right) \quad \text{high-angle (Suortti)}$$

CPS scans



Useful for having bot specular and off-specular signals in one scan

Full-Profile Search-Match (FPSM)

a free internet tool for phase ID and Quant

Diffraction pattern and sample composition

Upload diffraction pattern:

Atomic elements in the sample:

Sample nanocrystalline

Experiment details

Radiation:

X-ray tube:

Other : x-ray Wavelength (Å):

Instrument geometry:

Bragg-Brentano (theta-2theta)

Bragg-Brentano (2theta only), omega:

Debye-Scherrer

Transmission

Instrument broadening function:

Extra output (for debugging)

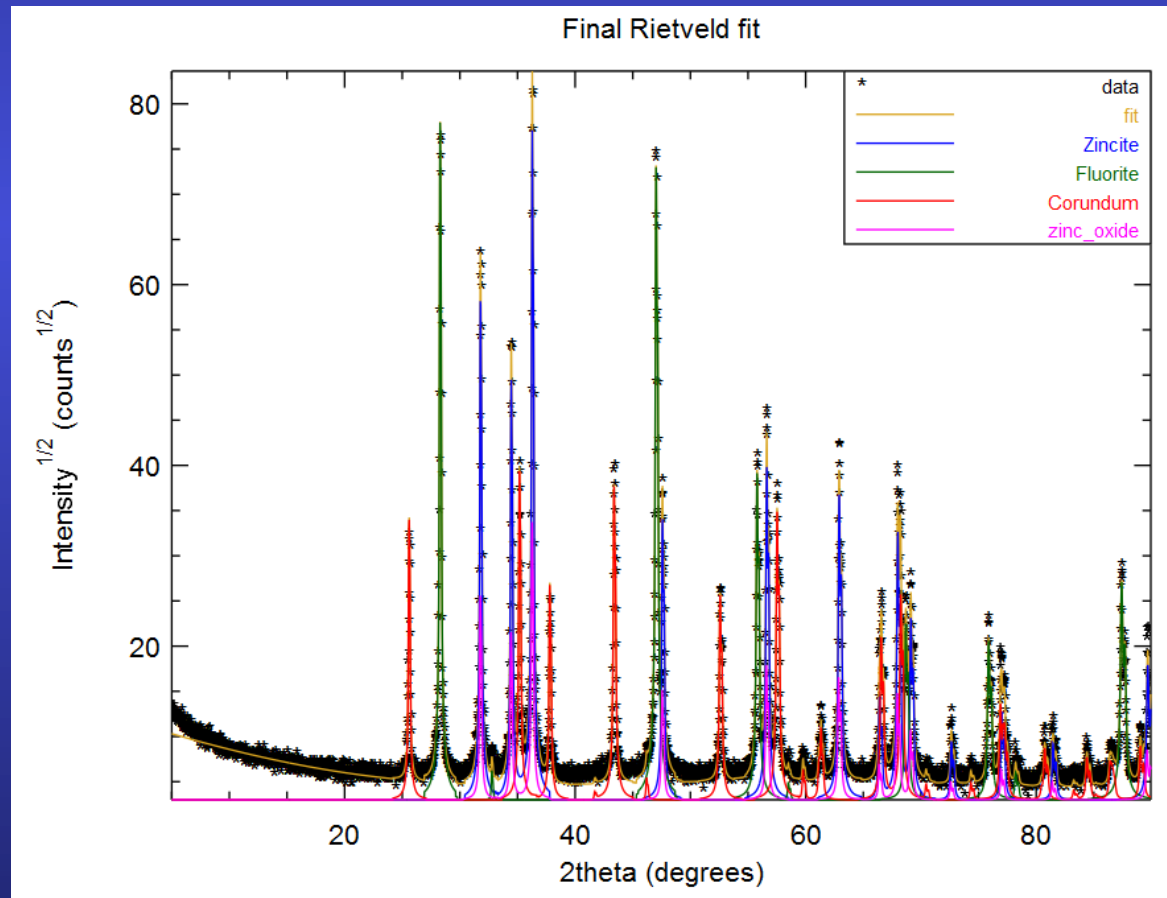
Structures database:

1 min later
>280000 COD
structures

Found phases and quantification:

| Phase ID | name | vol. (%) | wt. (%) | crystallites (Å) | microstrain |
|-------------------------|------------|----------|---------|------------------|-------------|
| 9004178 | Zincite | 16.8284 | 23.9708 | 2148.26 | 0.00028435 |
| 9009005 | Fluorite | 42.5522 | 33.9388 | 2117.08 | 0.000363147 |
| 9007498 | Corundum | 37.2197 | 37.2493 | 1889.82 | 0.000267779 |
| 2300112 | zinc_oxide | 3.39971 | 4.84114 | 1754.74 | 6.98311e-05 |

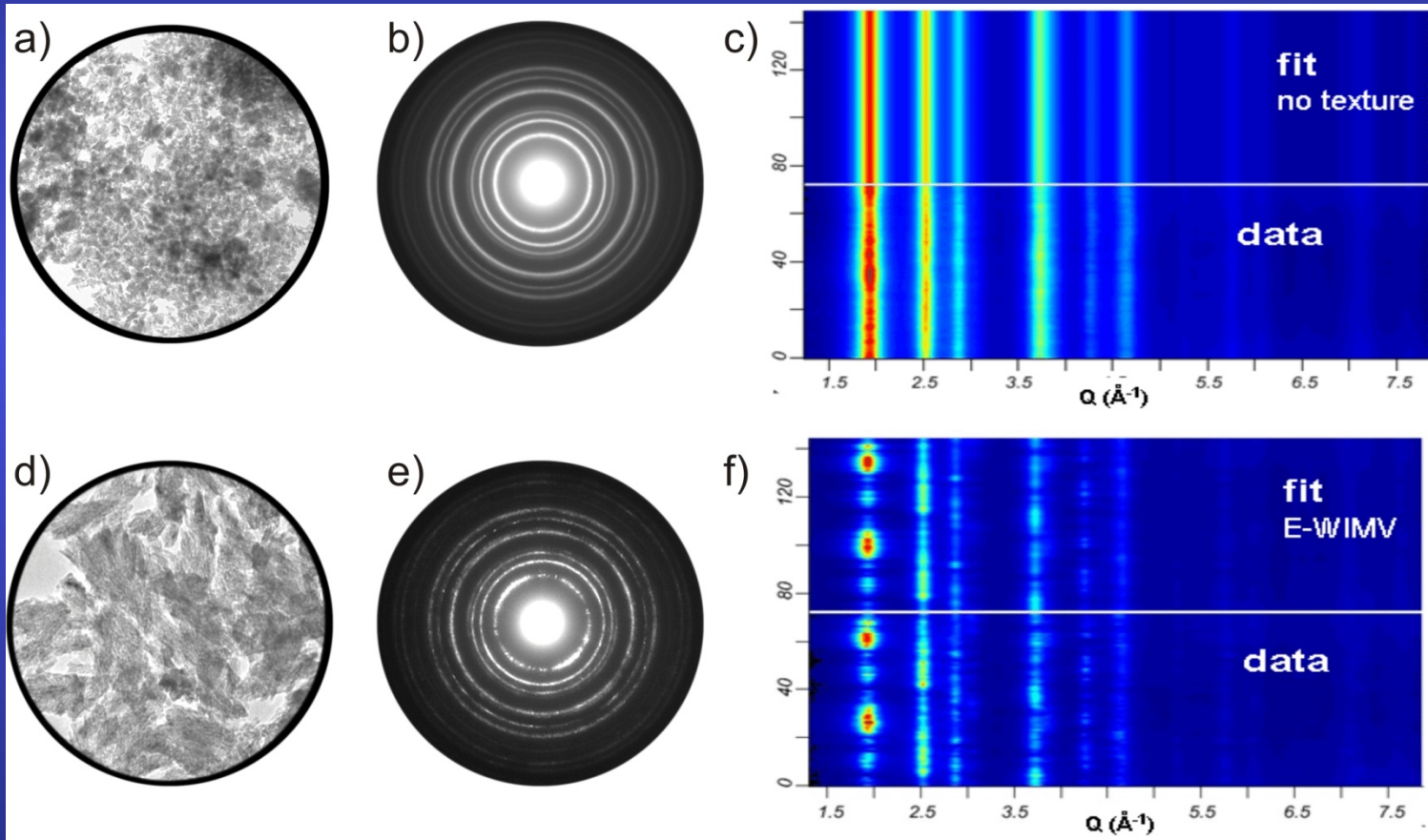
Final Rietveld analysis, R_w: 0.159468, GofF: 1.95869



TEM + QTA: local vs global

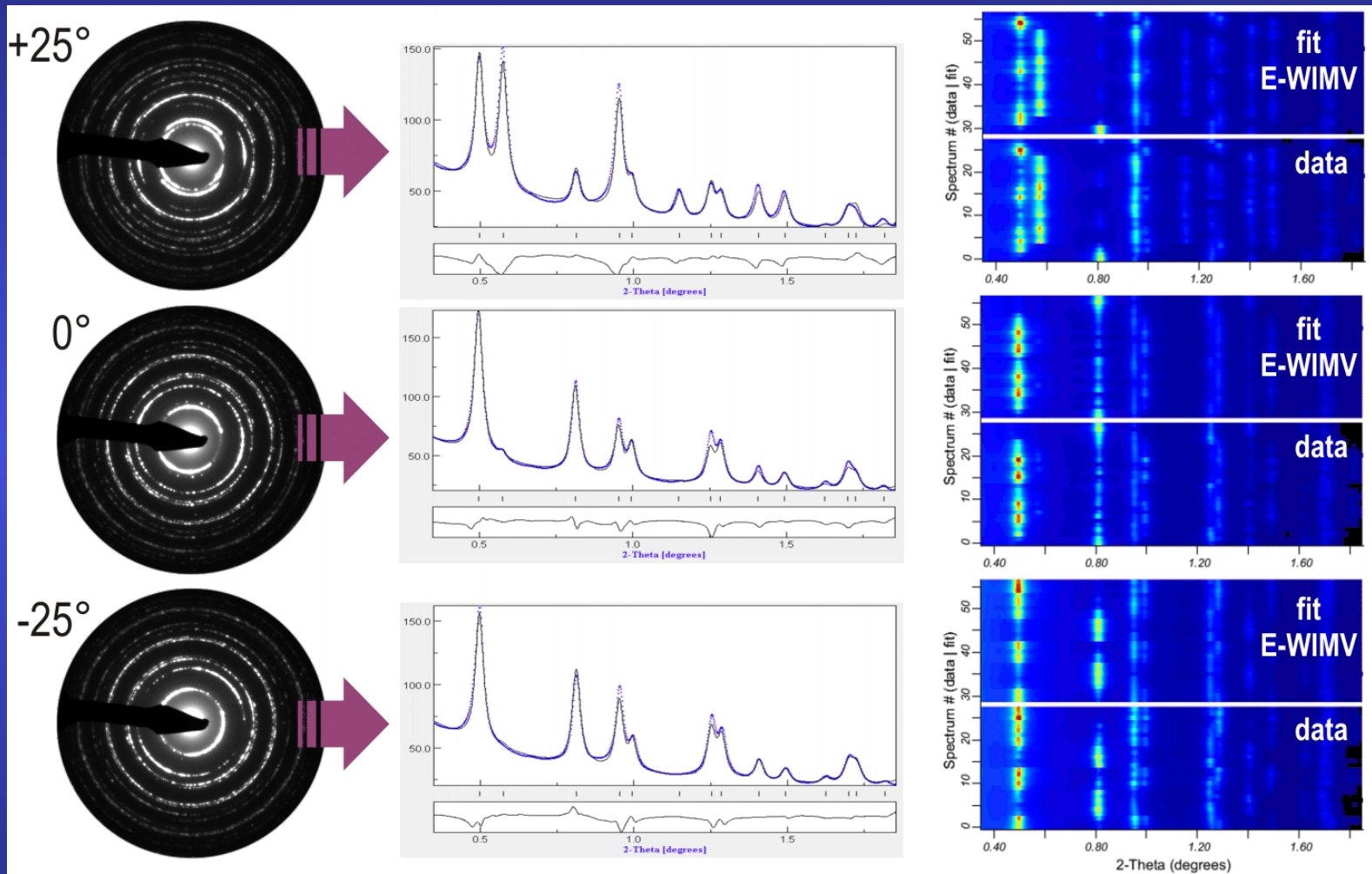
Pt thin film on Si

a) 6 μm diameter selected area, b) EPD and c) 2D plot.



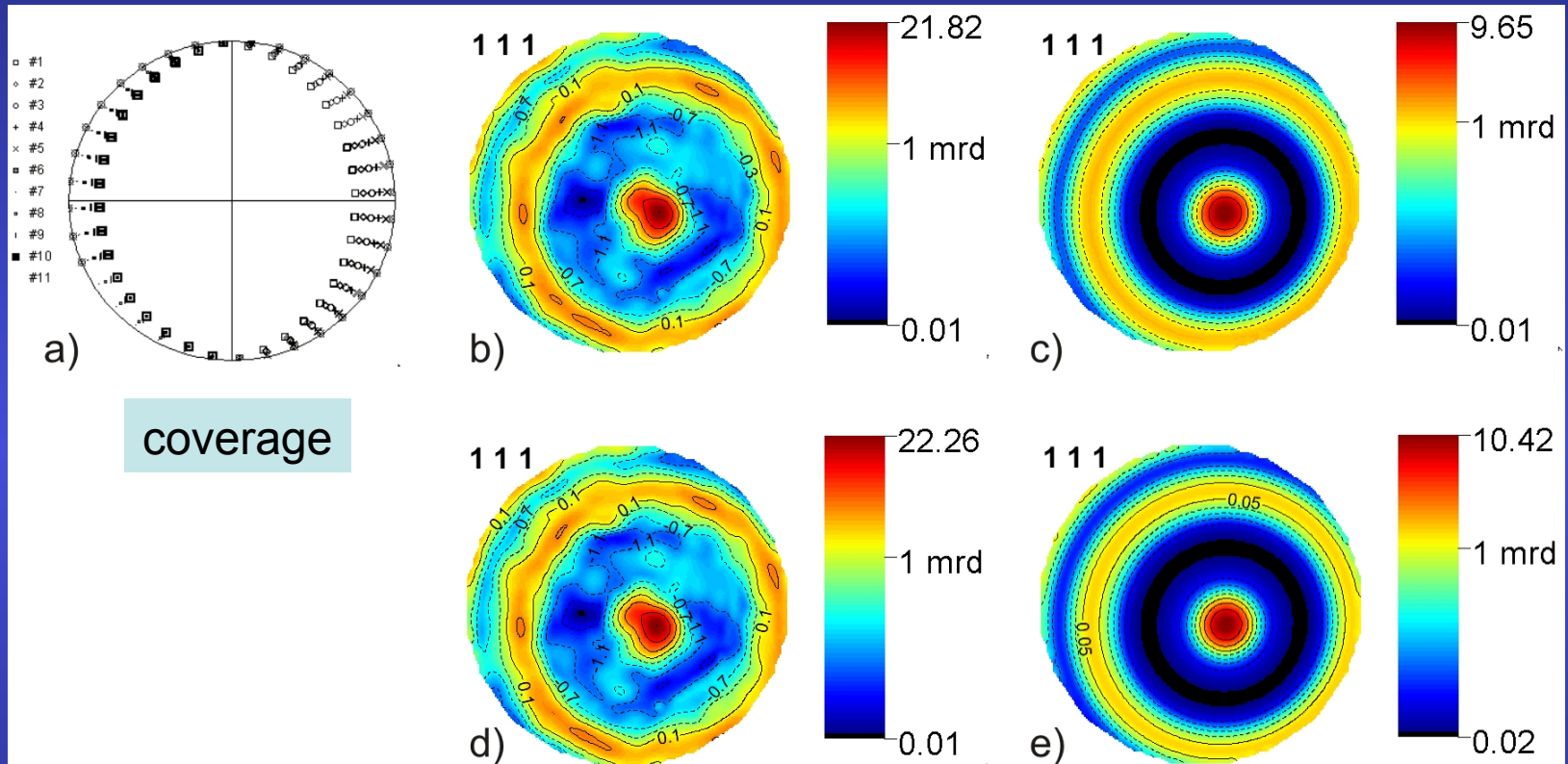
d) 0.5 μm diameter selected area, e) EPD and f) 2D plot

Patterns taken from $+25^\circ$ to -25° (step 5°) tilts: thin film prepared for TEM plan view



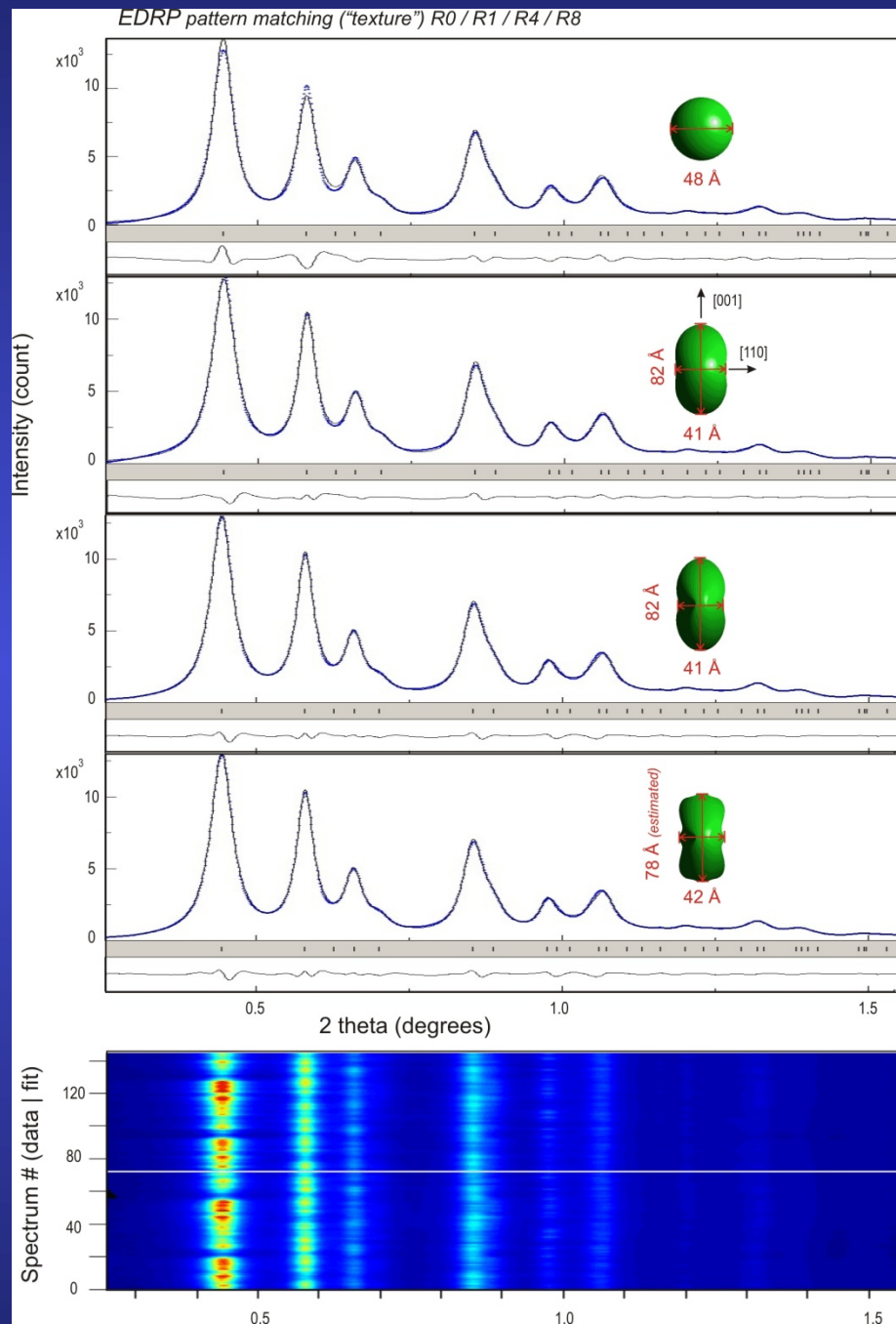
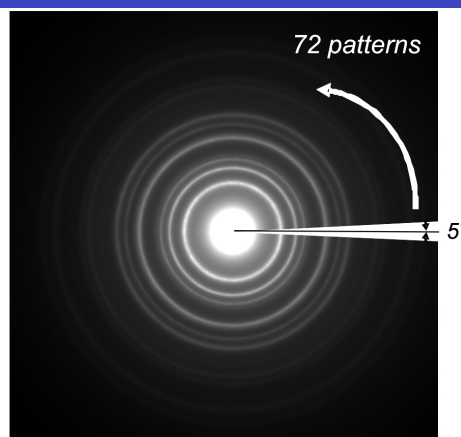
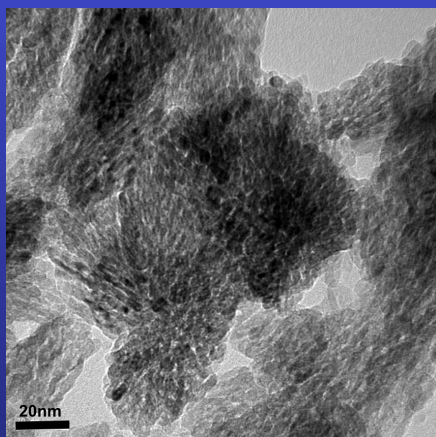
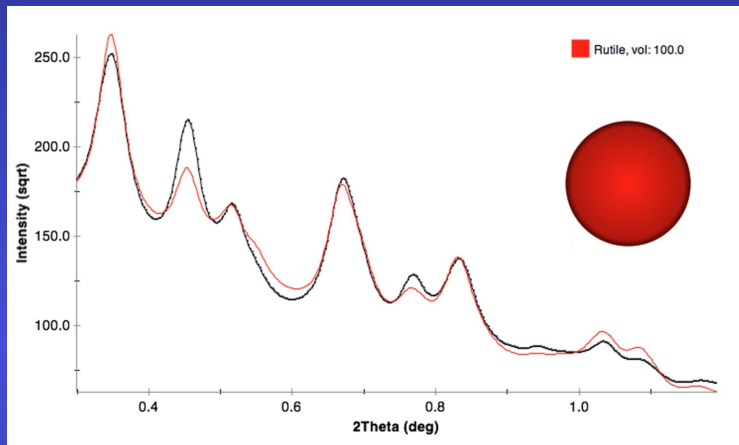
3 out of 11 EPD, 1D and 2D plots. Pattern matching (Pawley)

Pawley pattern matching
 EWIMV Fiber component

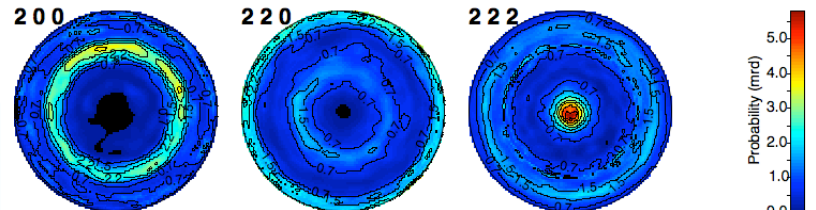
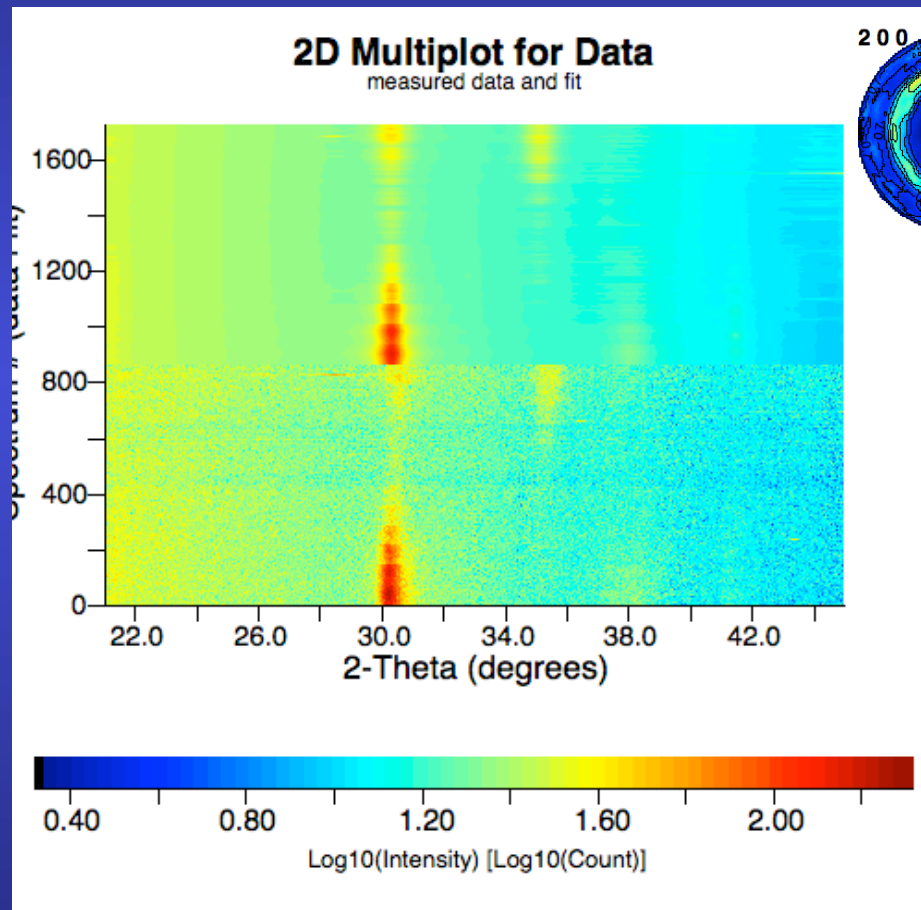


EWIMV Fiber component
 2-beams dynamical (Blackman)

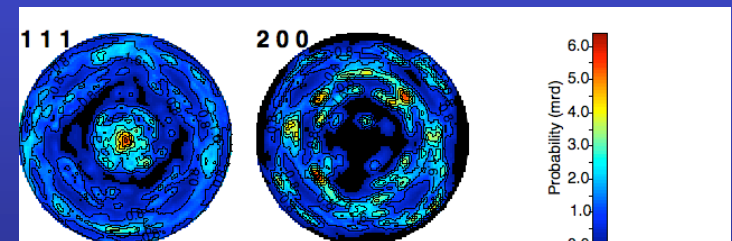
TEM + QMA: TiO₂ nanopowder



XRF + XRR + Combined Analysis: $\text{In}_2\text{O}_3/\text{Ag}/\text{In}_2\text{O}_3/\text{Si}$ stack

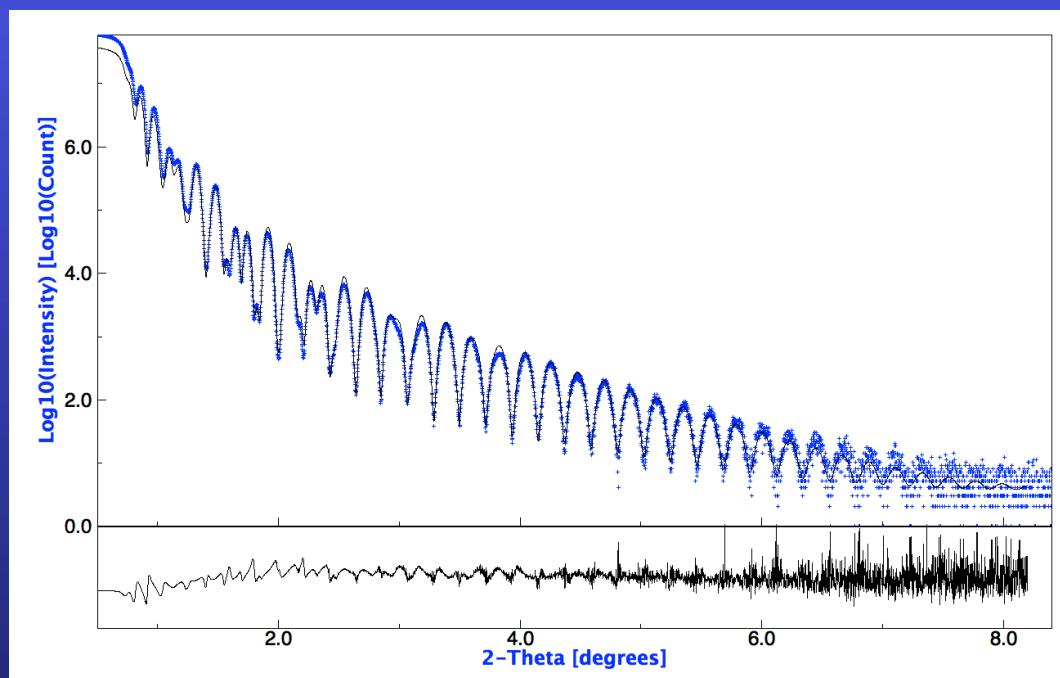
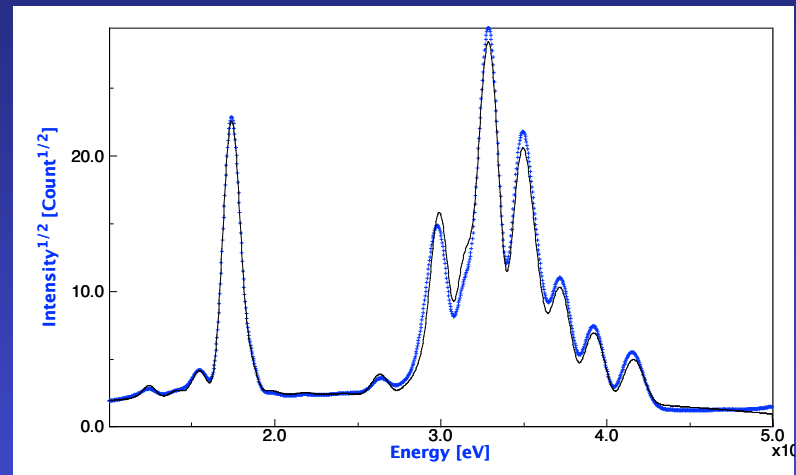
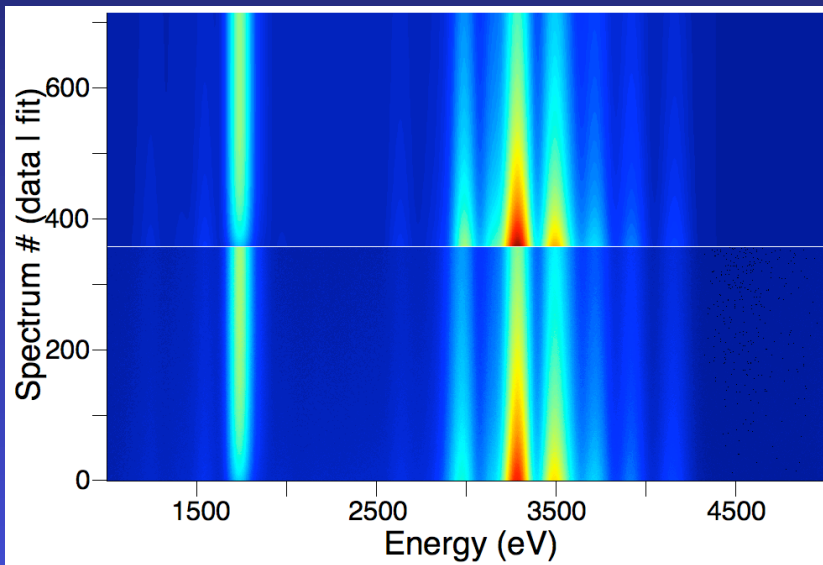


$a = 1.02104(5)$ nm
 $\langle R \rangle$ (spherical) : $153.2(5)$ nm
 $\sigma_{11} = 185(25)$ MPa

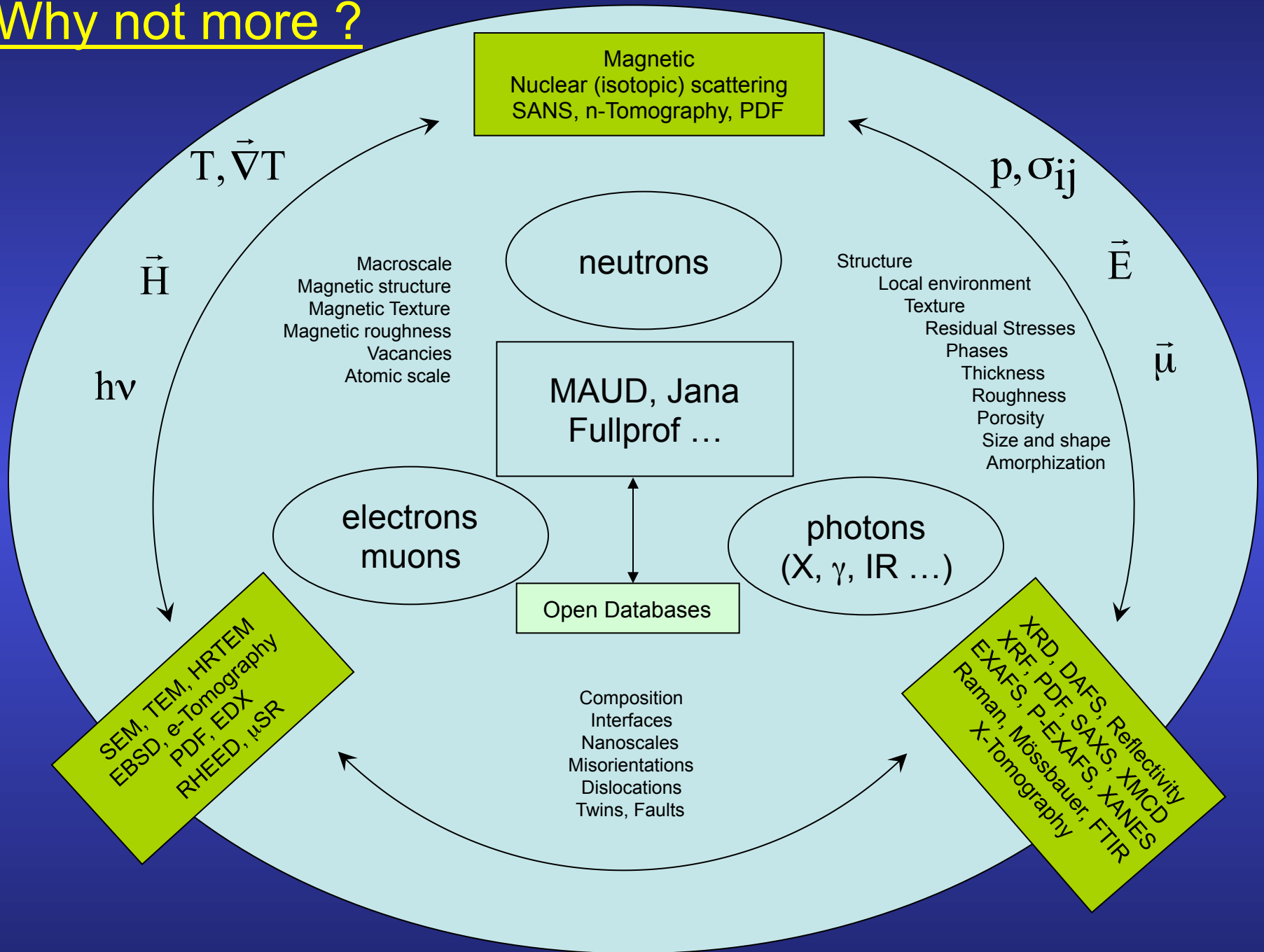


$a = 0.40943(7)$ nm
 $\langle R \rangle$ (spherical) : $97.4(1.3)$ nm

GoF = 1.09



Why not more ?



Conclusions

A lot of problems can be solved !

Texture helps to resolve them: good for real samples, good for nanomaterials description !

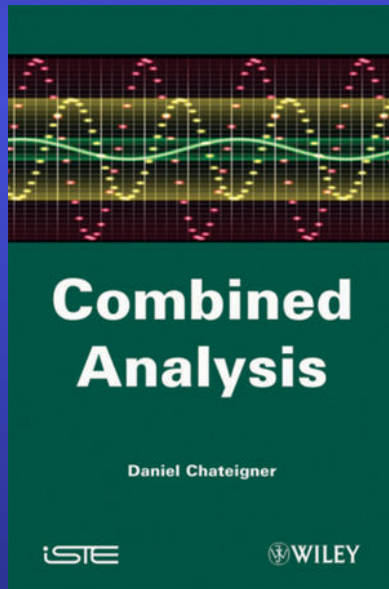
Anisotropy favours higher resolutions

Combined analysis may be a solution, unless you can destroy your sample or are not interested in macroscopic anisotropy ...

If you think you can destroy it, perhaps think twice

Combined Analysis Workshop in Caen:
30th June - 4th July 2014 !

www.ecole.ensicaen.fr/~chateign/formation/



Thanks !